

*Electrode Optimization Studies and  
Cathode Surface Chemistry:*

*Determination of Key Correlations  
between*

*Surface Features and Electrochemical Performance*

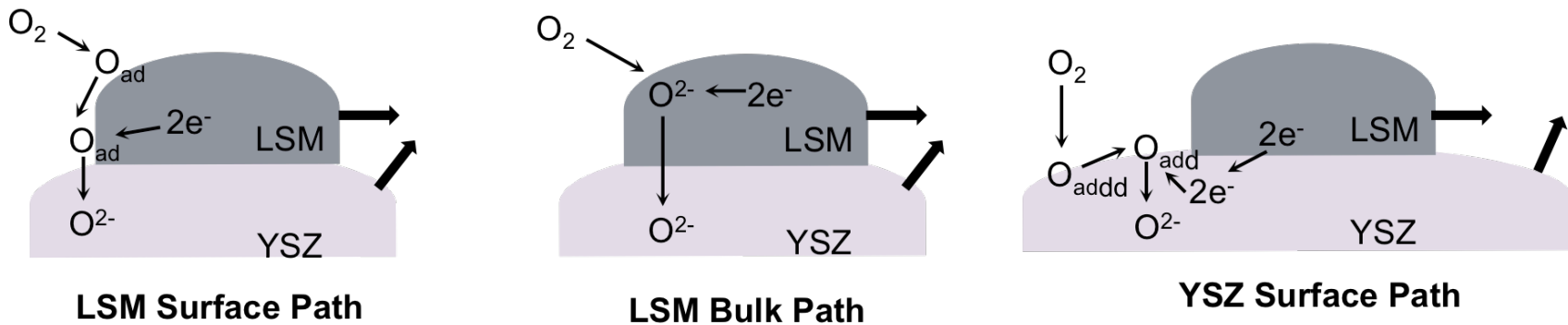
**Paul Salvador**

Department of Materials Science and Engineering,  
Carnegie Mellon University, Pittsburgh, PA, 15213

SECA Review August 6, 2008

*RDS-NETL-SECA: Briggs White and Wayne Surdoval*

# Thin Film Approach to Investigating Cathode Surface Chemistry



*There is reason to believe that the surface structure of known backbones is dynamic under load.*

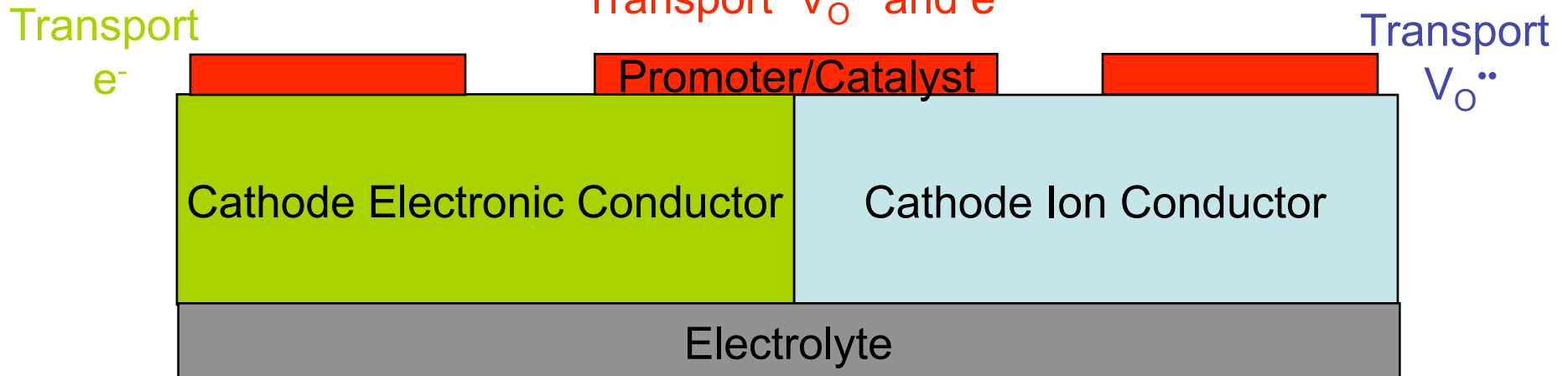
*There is no reason to believe that the ideal backbone will have the ideal surface kinetics.*

*Can we understand / engineer highly-active and stable surfaces?*

# Thin Film Approach to Investigating Cathode Surface Chemistry



Actively Reduces  $\text{O}_2$  and  
Transport  $\text{V}_\text{O}^{\bullet\bullet}$  and  $\text{e}^-$



*There is no reason to believe that the ideal backbone will have the ideal surface kinetics.*

*There is reason to believe that the surface structure of known backbones is dynamic under load.*

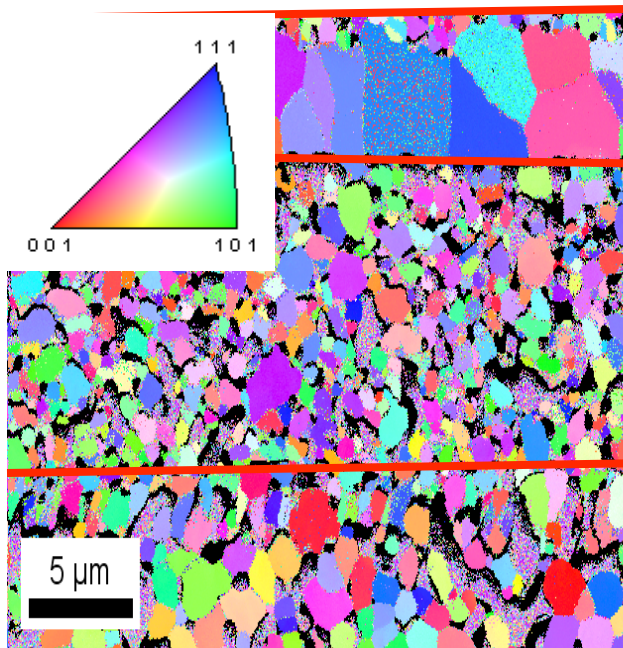
*Can we understand / engineer highly-active and stable surfaces?*

# Orientation Mapping Of Internal Interfaces:

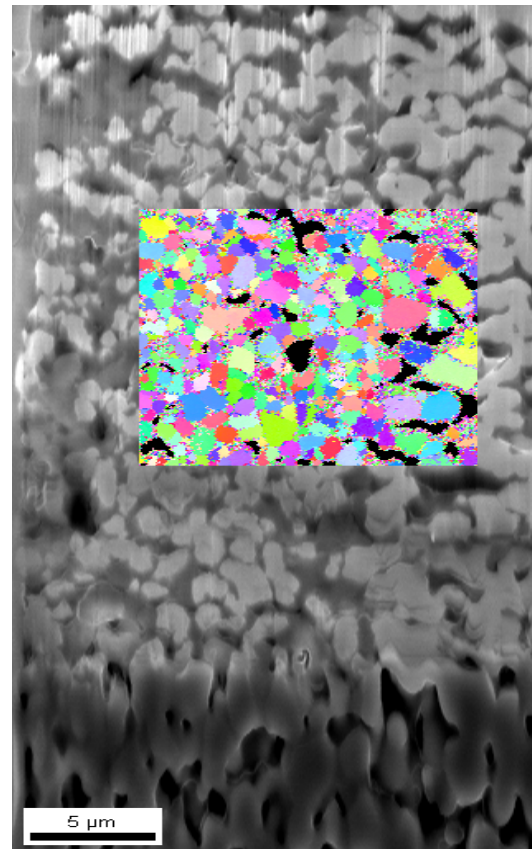
NETL – Carnegie Mellon – NSF MRSEC

## Statistical Information on Interfacial Crystallography

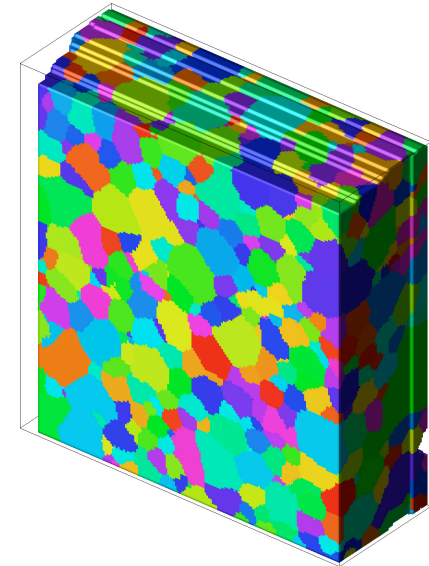
2D Traditional OIM



2D FIB Based OIM



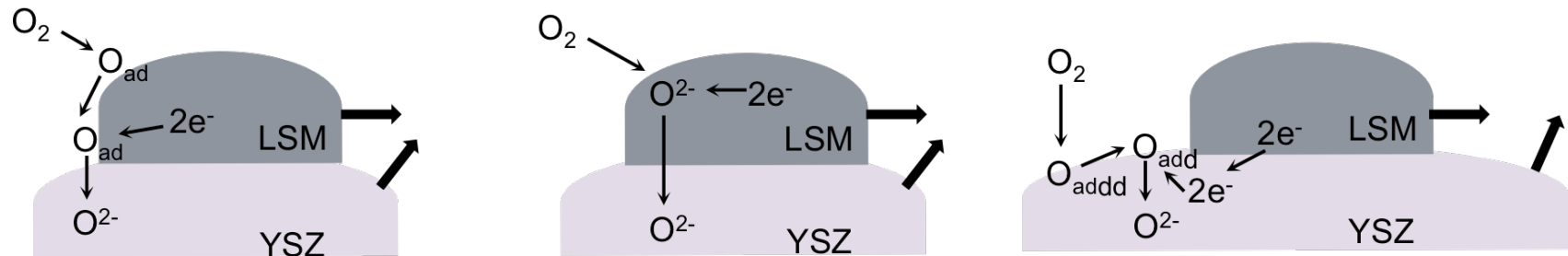
3D FIB Based OIM



**Have 3D Crystallography of Interfaces in all Cell Components  
Can Determine Relative Surface / Interface Energies**



# What happens during oxygen uptake?



**LSM Surface Path**

**LSM Bulk Path**

**YSZ Surface Path**

## • *Adsorption*

- *Mass of Material* (Gravimetry)
- *Surface Chemistry* (Spectroscopy)
- *Surface Electronic Structure* (Kelvin Probe, STS, Normal Conductivity)

## • *Electronic transfer*

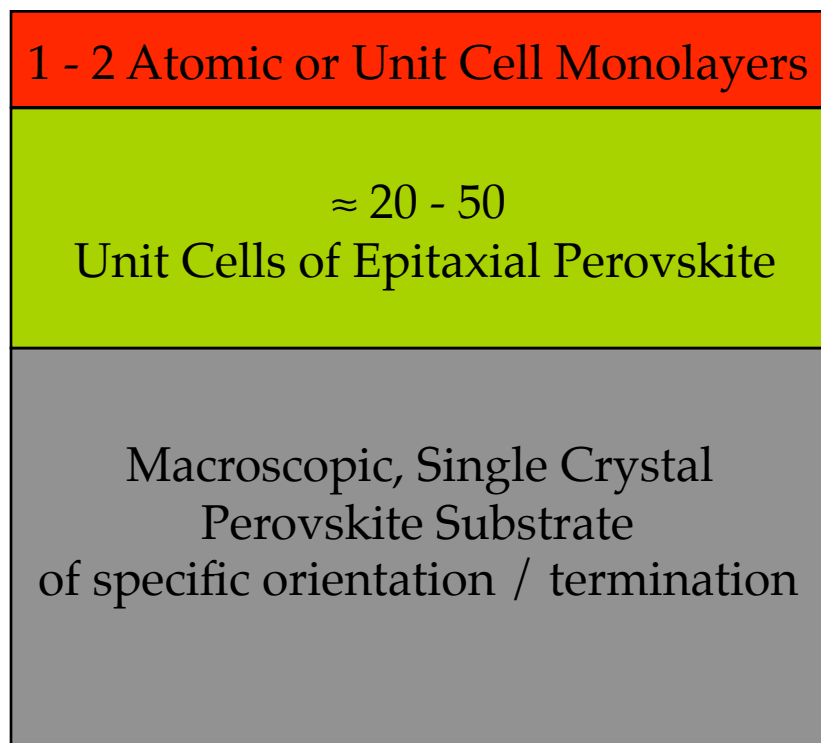
- *Consumption of holes* (Parallel Conductivity / Thermopower)
- *Fermi Level Changes* (Kelvin Probe / STS)
- *Surface chemistry* (Spectroscopy)

## • *Oxygen Vacancy Filling*

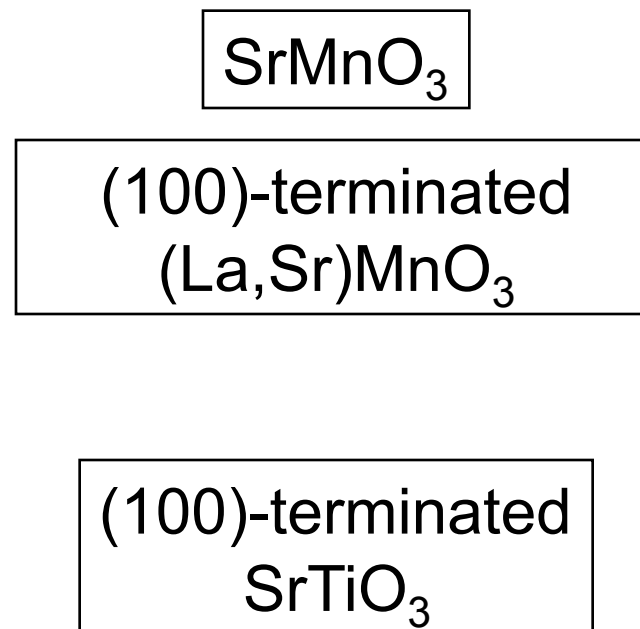
- *Mass Change* (Gravimetry)
- *Total charge density* (Conductivity / Thermopower)
- *Surface Chemistry* (Spectroscopy)

# “Ideal” Surface Science Sample

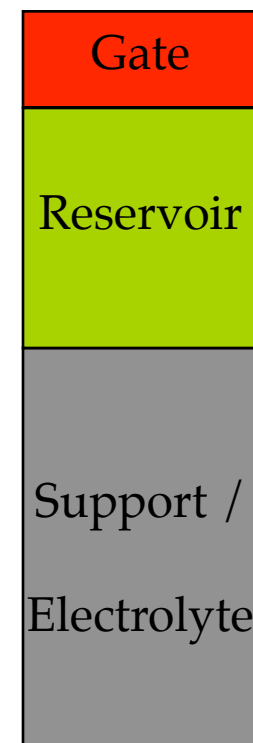
## General Schematic



## Example



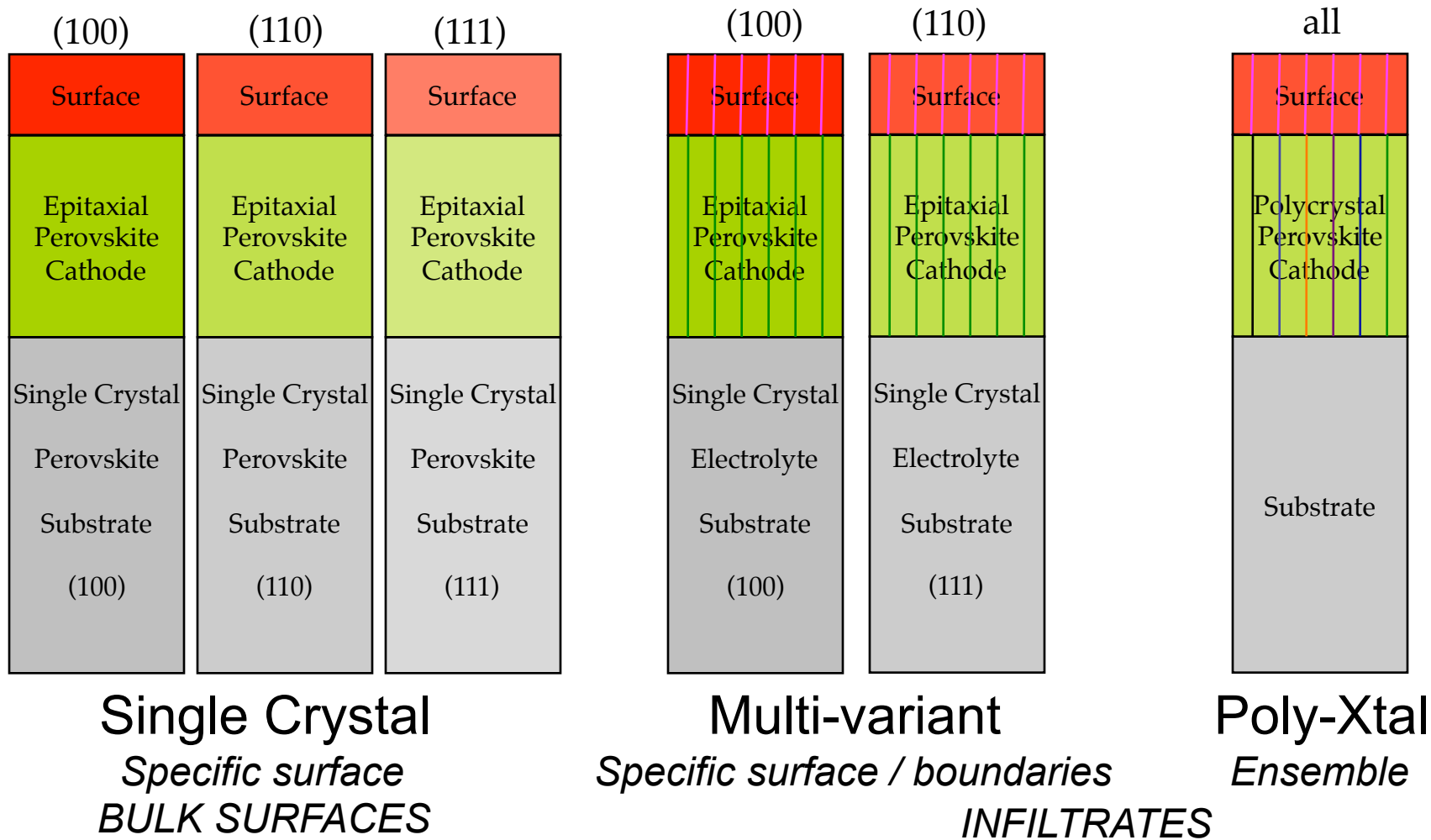
## Concept



*Control Microstructural Complexity and Surface Crystallography*

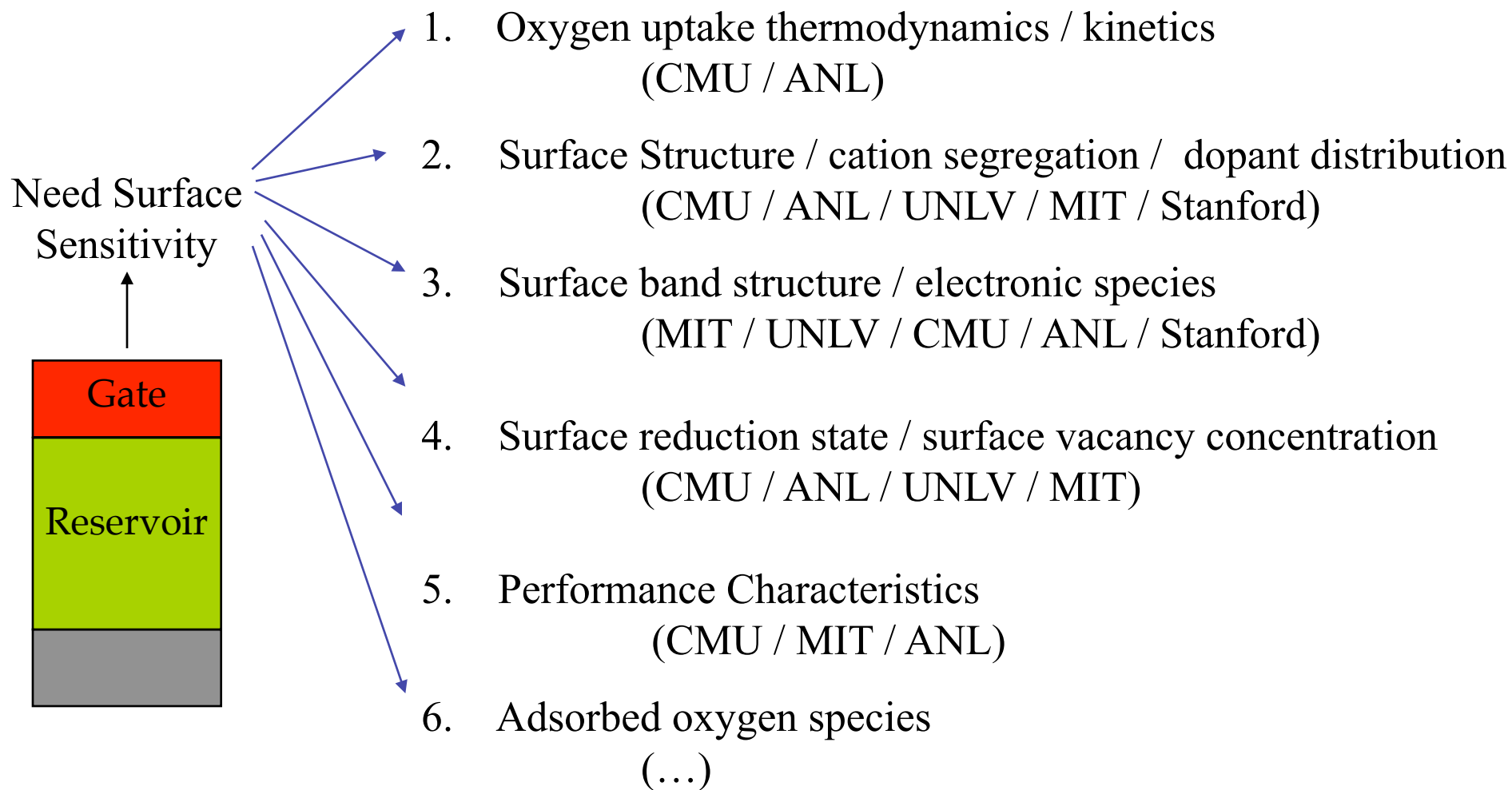
# Thin Film Samples Driving Surface Science

Films Allow for Surface / Microstructural Control



**Important to synthesize each version of these.**

# Experimental Values of Interest that are in Dynamic Equilibrium



# Collaborators

## Surface Engineering / Characterization / TEM

B. Kavaipatti, L. Yan, S. Wang, R. Petrova  
Carnegie Mellon

## Surface Stability / Interface Stability

L. Helmick, S. Seetharaman  
Carnegie Mellon

R. Gemman, K. Gerdes  
NETL

## Surface Chemistry

J. Kitchin, Carnegie Mellon

C. Matranga, NETL

## Detailed Structure and Surface Segregation vs

### Oxygen Activity

J. Eastman, D. Fong, P. Fuoss  
APS - ANL

## Detailed Structure and Surface Segregation vs

### Electrochemical Activity

K.-C. Chang, D. J. Myers, J. D. Carter, H. You  
APS-ANL

B. Yildiz, MIT

## Electrochemical Activity and Surface Chemistry

B. Ingram, T. Cruse, M. Krumpelt  
ANL

## Electronic Structure

Salvador, Carnegie Mellon

W. Harrison, Stanford

C. Heske, UNLV and B. Yildiz, MIT

Y. Mantz, NETL



# CMU Work for Cathode Surface Science Project

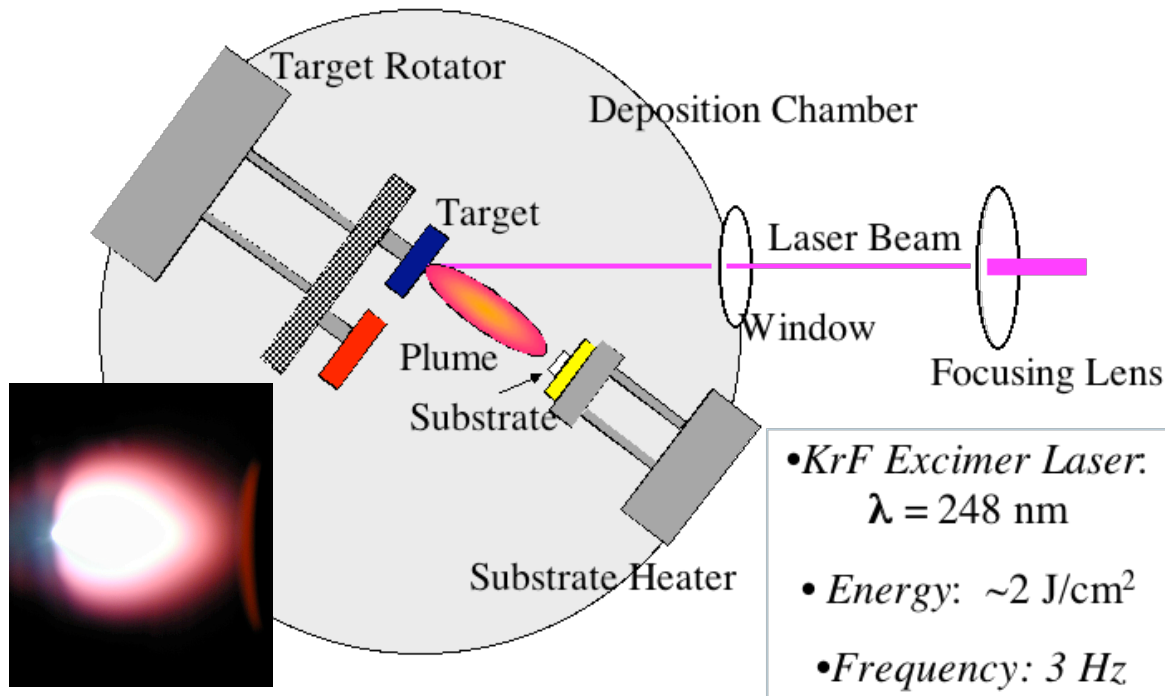
- ***Growth of High-Quality Thin Film Samples***
  - *Perovskite / Perovskite Epitaxy and Surface Control*
  - *Perovskite / Fluorite Epitaxy and Surface Control*
  - *Generation of Surface-Modified Samples*
- ***Surface Kinetics for Oxygen Uptake***
  - *Electrical Conductivity Relaxation*
  - *Piezoelectric Crystal Microbalance Gravimetry*
  - *Kelvin Probe Spectroscopy*
- ***Surface Thermodynamics of Oxygen Uptake***
  - *Piezoelectric Crystal Microbalance Gravimetry*
  - *Kelvin Probe Spectroscopy*
- ***Electronic Structure***
  - *Kelvin Probe Spectroscopy*
  - *STM (MIT)*
- ***Ex-situ Surface Characterization for Correlations***
  - *Scanning Auger / XPS*

# Pulsed Laser Deposition Laser MBE / MBE

## Advantages of PLD

- Targets made via standard methods.
- Stoichiometric transfer from target to film
- High-quality epitaxial films for complex oxides
- High-Quality Metal Films
- Simple, versatile, and relatively inexpensive
- House 6 targets at once

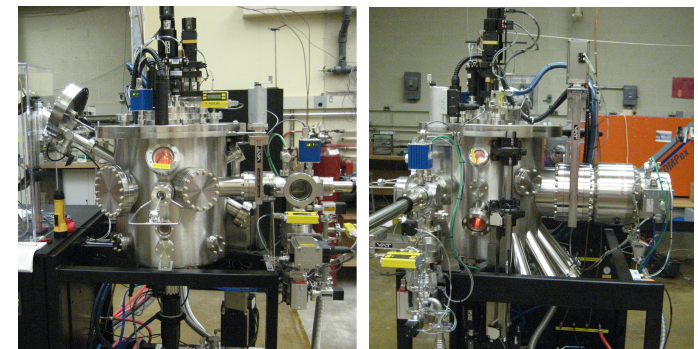
## *Pulsed Laser Deposition*



## Deposition Parameters

PRESSURE : 0.00001 - 0.2 Torr  
TEMPERATURE: RT - 950 °C  
FLUENCE : 1-8 J/cm<sup>2</sup>  
FREQUENCY : 1-10 Hz  
COOLING: 0.00001- 300 Torr

Depositions : 1- 4 hrs Max  
3 - 4 depositions / day  
3 - 4 samples / deposition

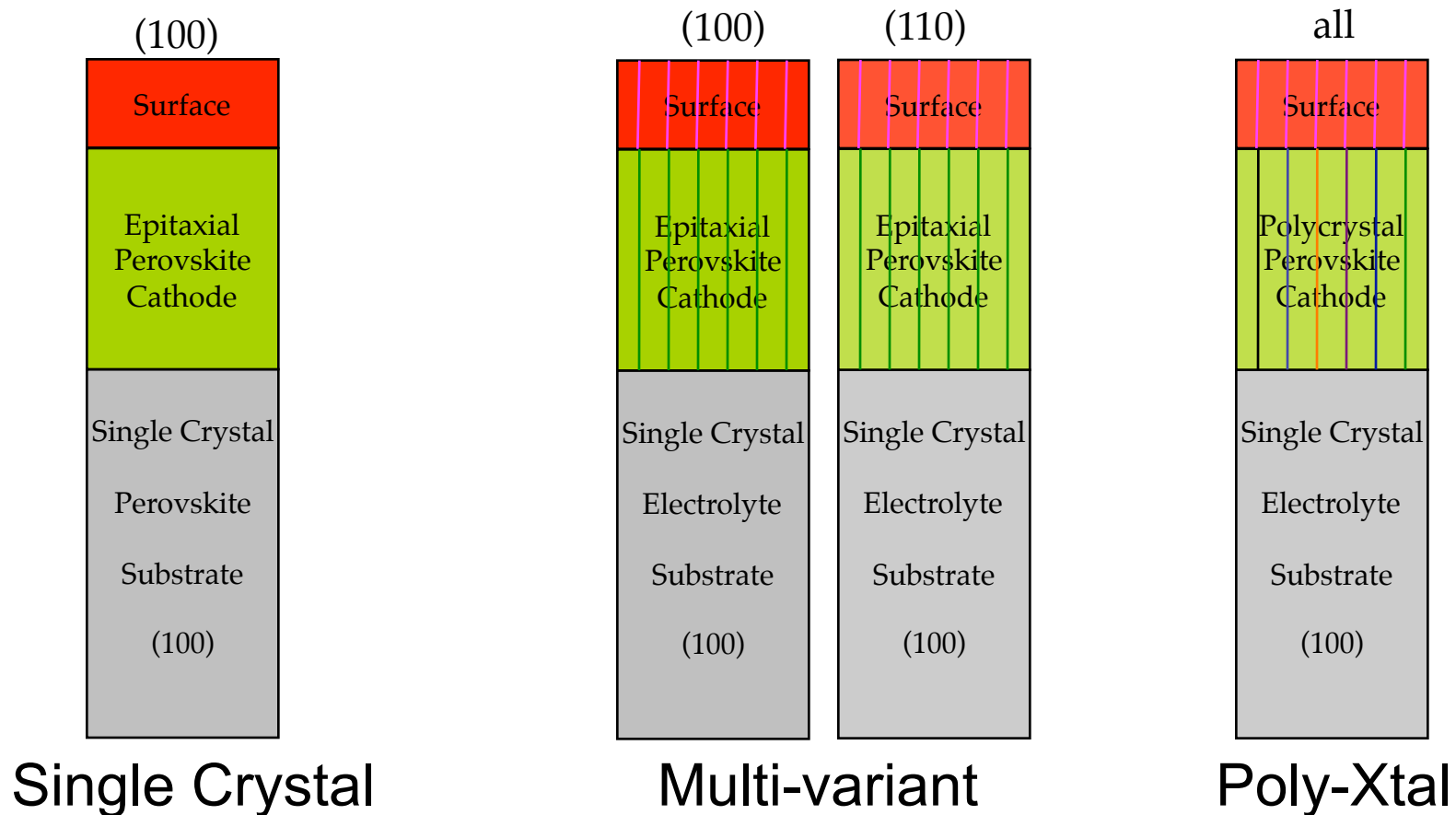


# The Natural Starting Point Seems to be YSZ (100)

Ideal substrate to do electrochemistry

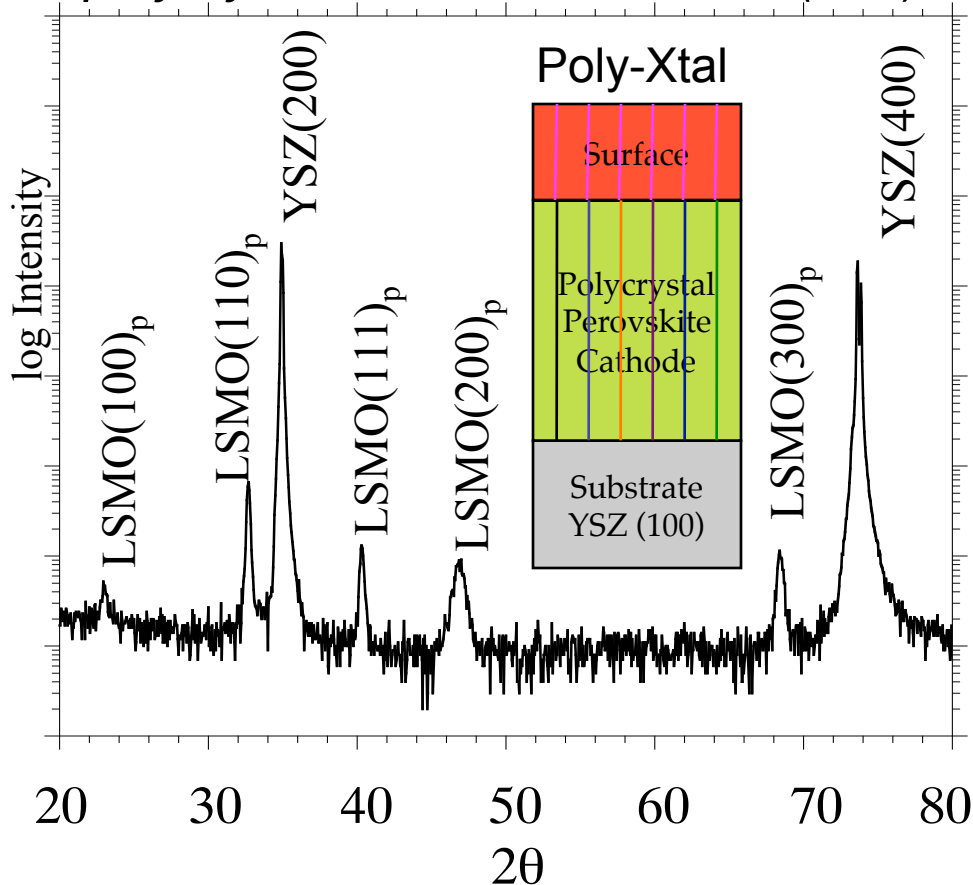
Ideal Substrate to correlate to real SOFC cathodes

Can we get surface engineered samples routinely?



# *(La,Sr)MnO<sub>3</sub> thin films on YSZ(100)*

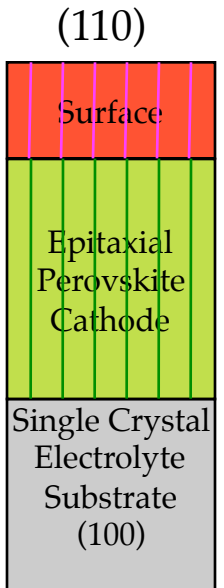
*Film prefers to grows in a polycrystalline fashion on YSZ(100)*



*Good for comparison to real SOFC*

*Poor for Surface Science*

*(110) Textured films are strong function of conditions not fully textured*



*Perovskite / Fluorite Interface in ESSENTIAL in final ION TRANSFER  
But we need better growth*

# Focus on Epitaxial Films with Controlled Surfaces

(100)	(110)	(111)
Surface	Surface	Surface
Epitaxial Perovskite Cathode	Epitaxial Perovskite Cathode	Epitaxial Perovskite Cathode
Single Crystal Perovskite Substrate (100)	Single Crystal Perovskite Substrate (110)	Single Crystal Perovskite Substrate (111)

Single Crystal

- *Many Available Commercial Substrates*
  - *SrTiO<sub>3</sub> (100), (111), (110)*
  - *Nb-doped SrTiO<sub>3</sub> (100), (110), (111)*
  - *LaAlO<sub>3</sub> (100)*
  - *NdGaO<sub>3</sub> (100), (110)*
  - *DyScO<sub>3</sub> (100)*
  - *LSAT (100)*
- *Can vary widely*
  - *Chemical elements in substrate*
  - *Strain state*
  - *Crystal Symmetry*
  - *Surface Morphology*
  - *Conductivity (e<sup>-</sup> / ion)*
  - *Dislocation content*
- *Generates IDEAL surfaces for investigation*
- *How do film properties depend on substrate?*



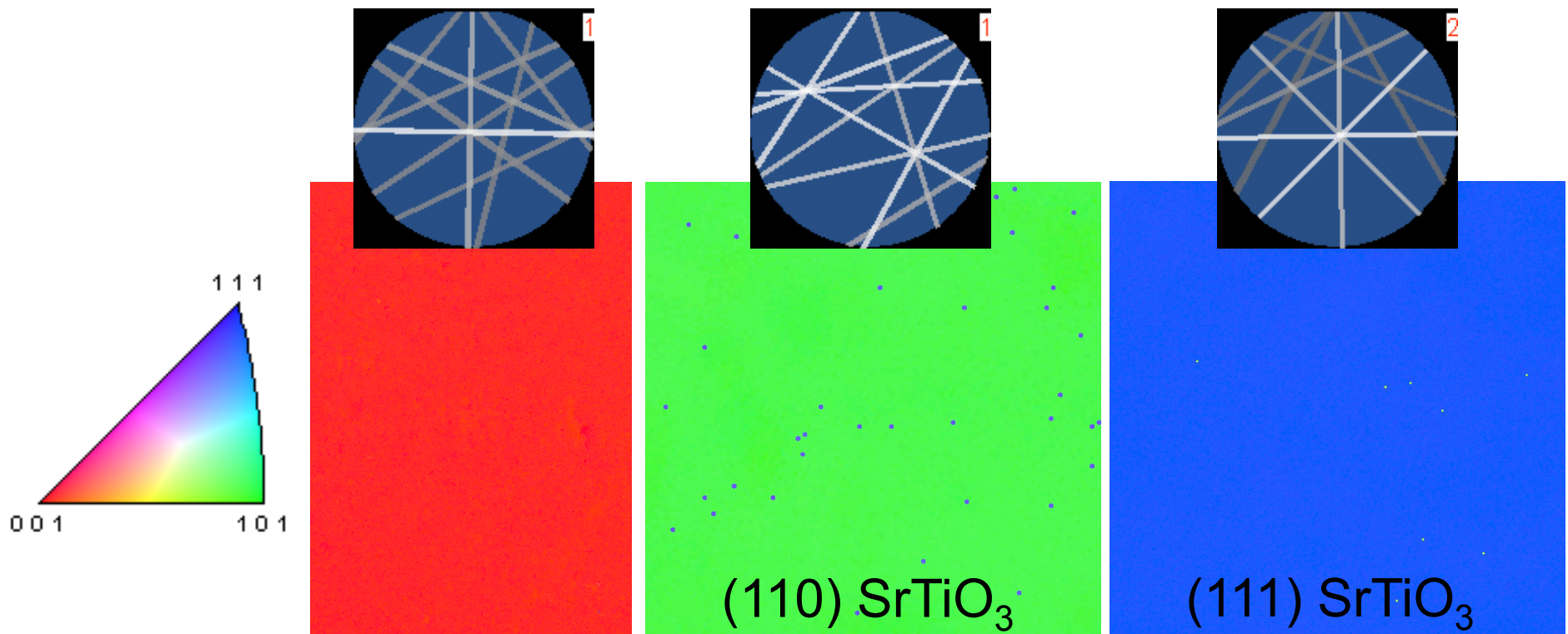
# Epitaxy along various Orientations

## Orientation Mapping / Surface Sensitivity

*Electron Back-Scattered Diffraction used to Identify Local Orientations*

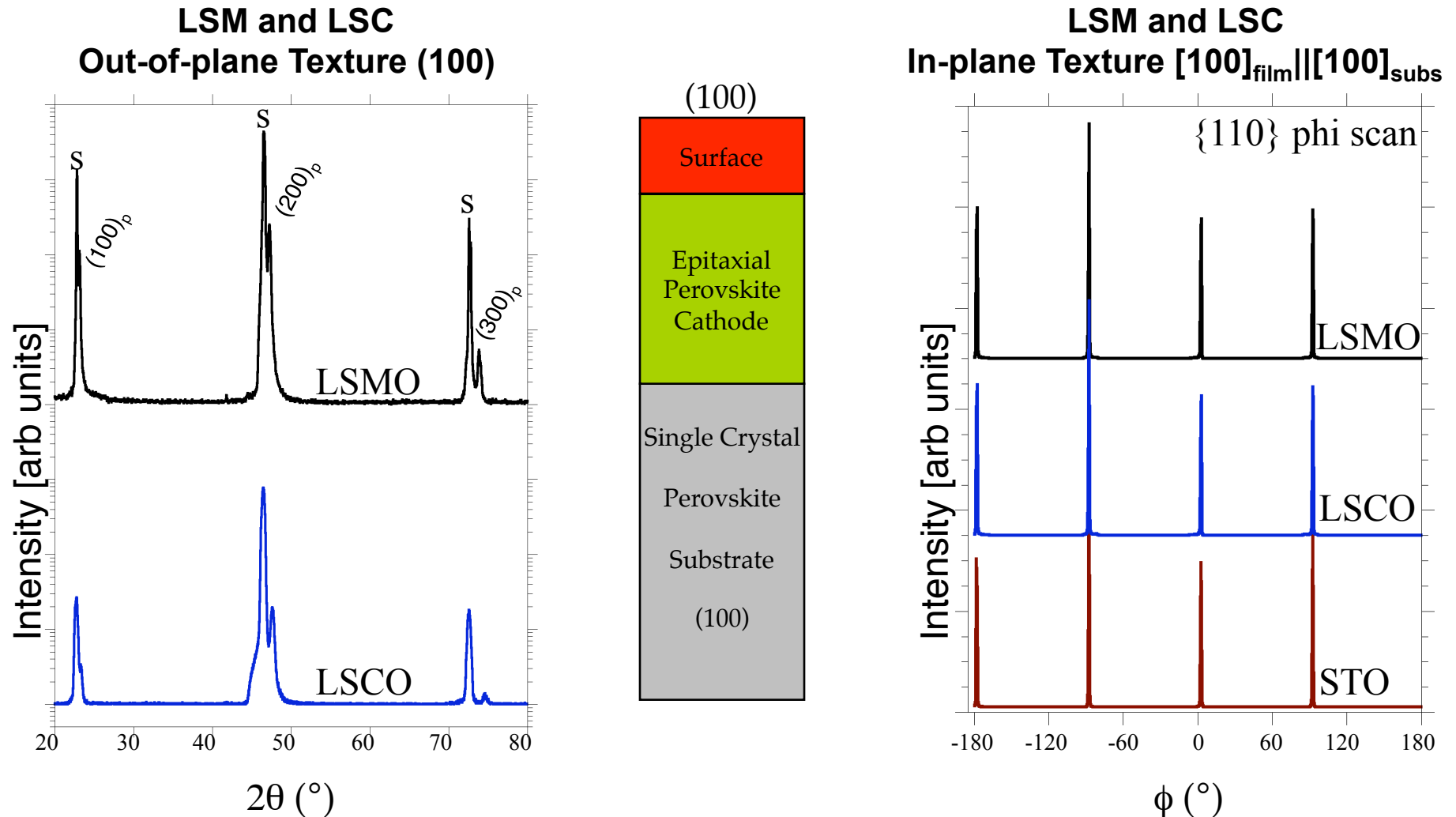
*$\text{La}_{0.7}\text{Sr}_{0.3}\text{MnO}_3$  (50 nm) deposited on  $\text{SrTiO}_3$*

*All scan areas > 20 x 20 micron<sup>2</sup>*



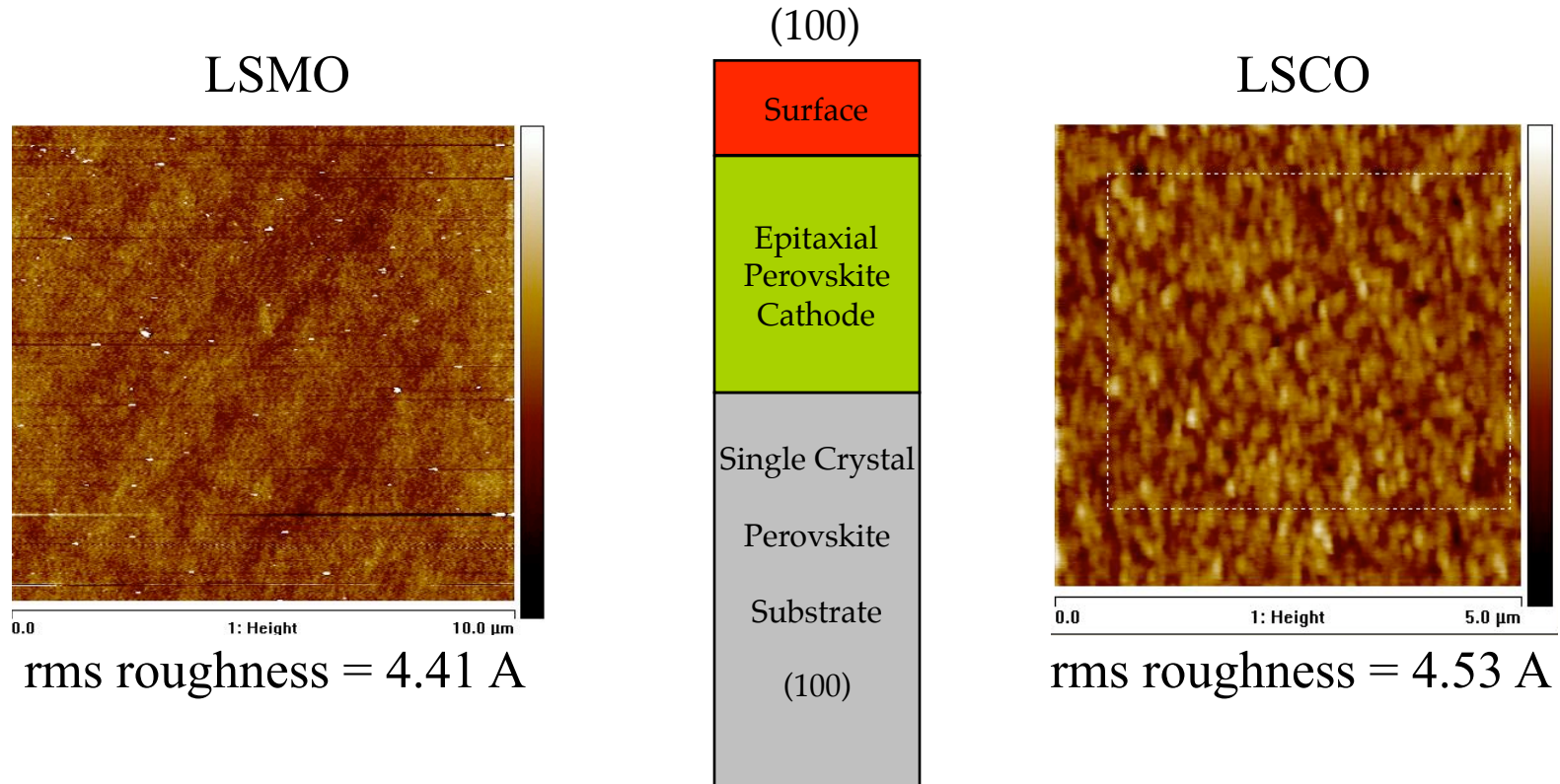
*All three low-index surfaces are obtained as epitaxial films*

# XRD: 60 nm LSMO and LSCO on STO(100) Perovskite – Perovskite Epitaxy



- *Perovskite - Perovskite Epitaxy is excellent for both film compositions*
- *Similar results are found for other orientations*

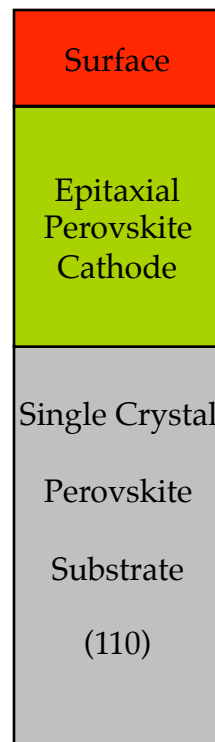
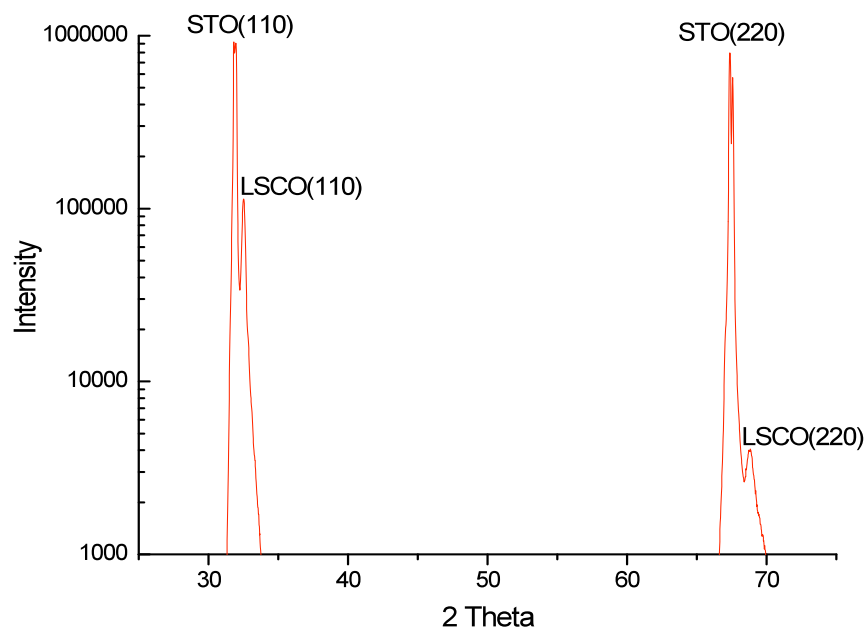
# AFM: 60 nm LSMO and LSCO on STO(100) Surface Features are Unit-Cell Smooth



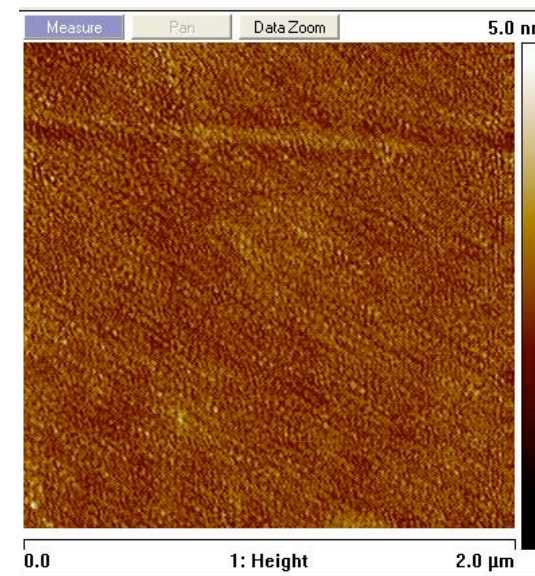
- *Surface Features are well defined*
  - *Films are atomically smooth*
  - *Required for surface sensitive X-ray / STS*
  - *Required for understanding overall surface response*
- *Similar results are found for other orientations*

# 60 nm LSCO on STO(110) XRD and AFM

## LSC Out-of-plane Texture (110)



## LSC Unit-cell smooth films



rms roughness = 2.91 Å

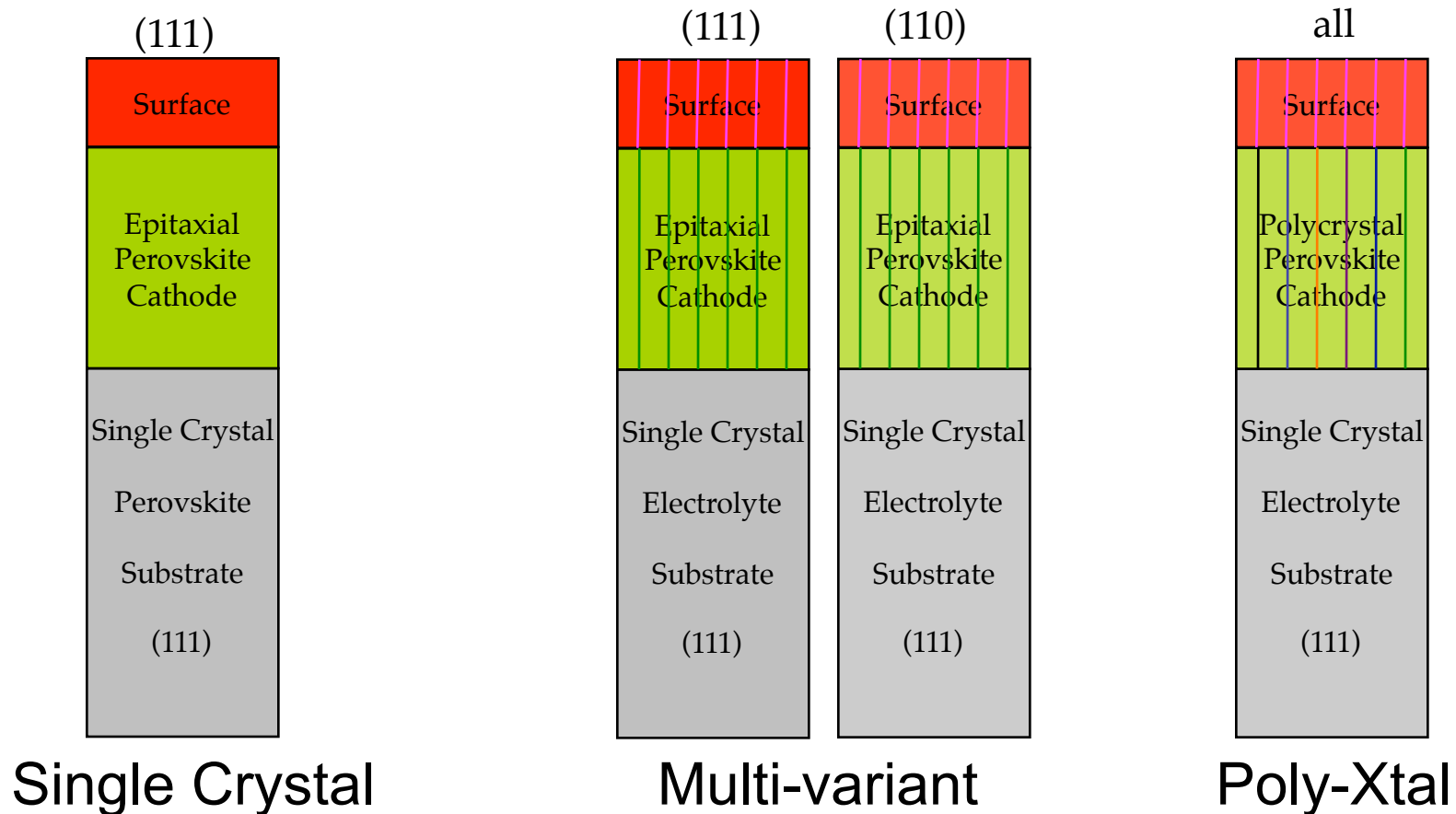
- *Perovskite - Perovskite Epitaxy is excellent for LSC in this orientation*
- *Similar results are found for other chemistries*

## Returning to Electrolyte Substrates: What Happens on YSZ (111)?

Ideal substrate to do electrochemistry

Ideal Substrate to correlate to real SOFC cathodes

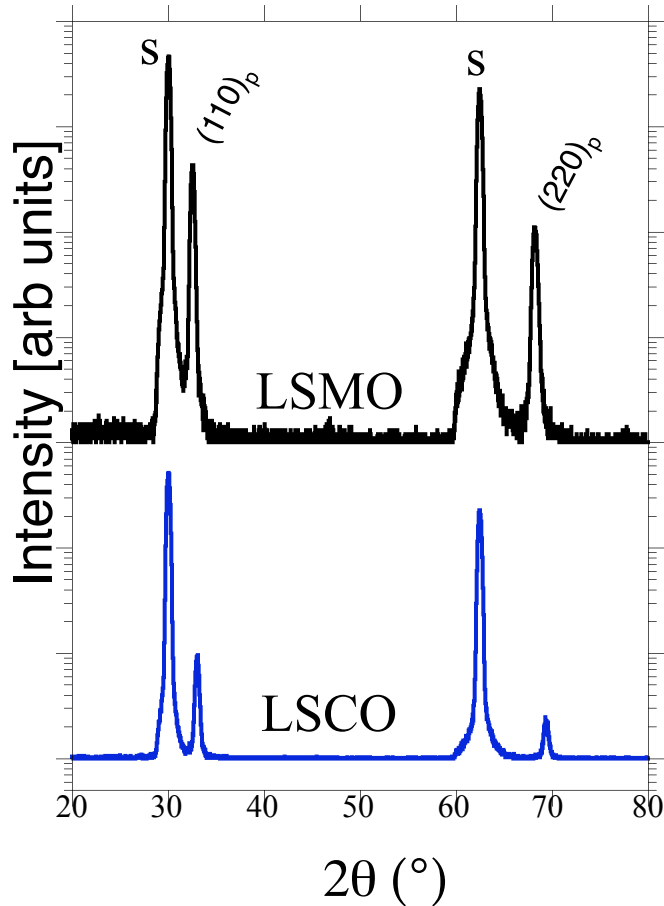
Can we get surface engineered samples routinely?



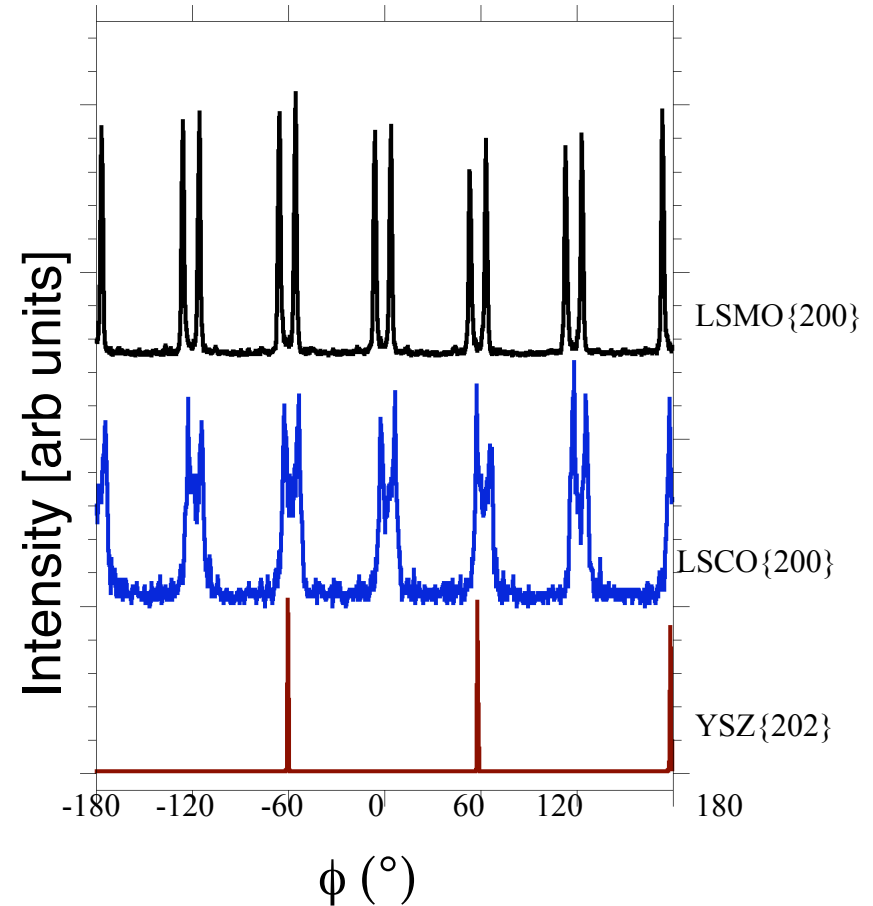


# XRD: 60 nm LSMO and LSCO on YSZ(111) Perovskite – Fluorite (electrolyte) Epitaxy

**LSM and LSC**  
**Out-of-plane Texture (110) on YSZ (111)**

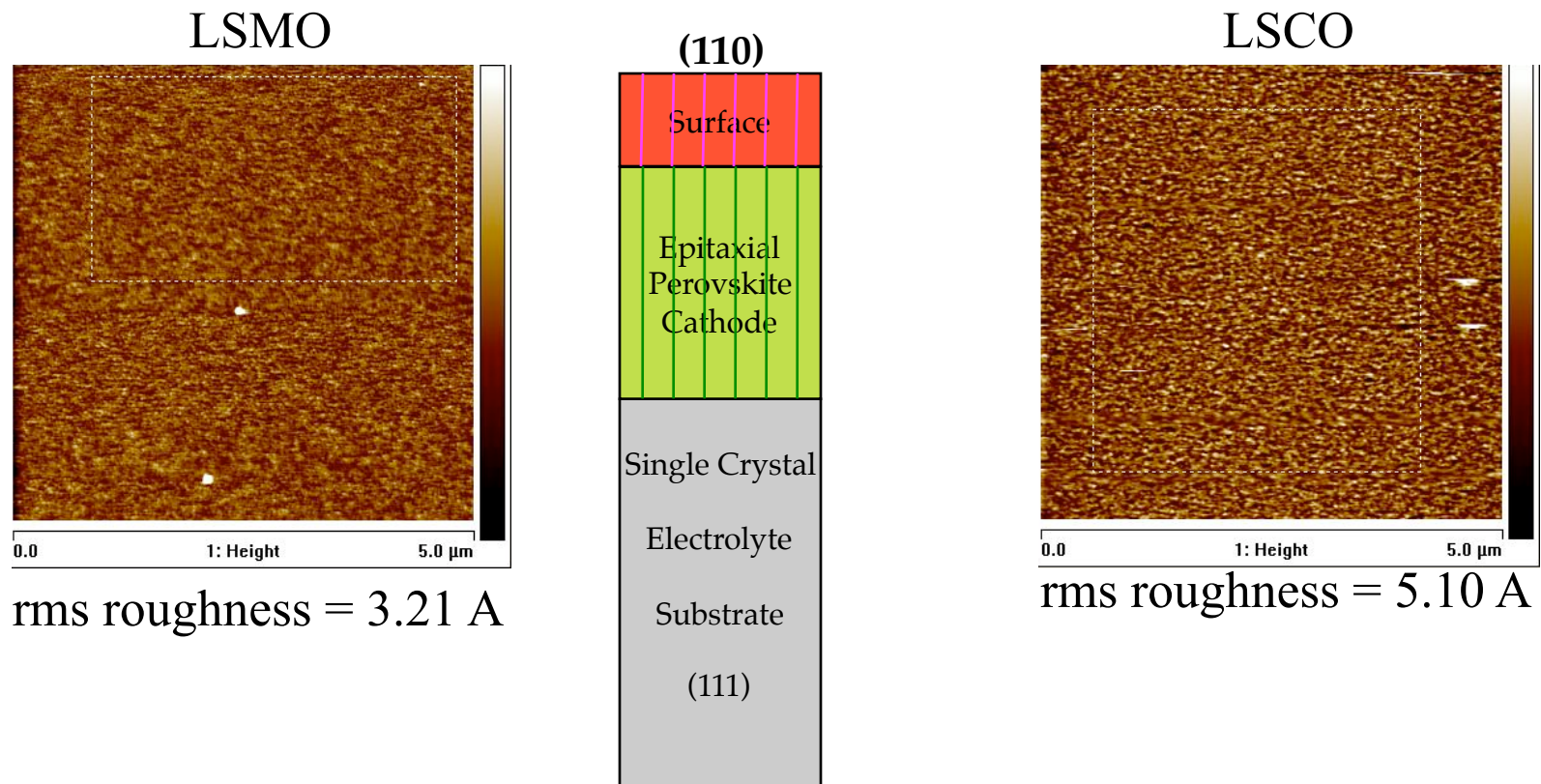


**LSM and LSC**  
**In-plane Texture  $[111]_{\text{film}} \parallel [11-2]_{\text{subs}}$**



- *Perovskite - Fluorite (YSZ) Epitaxy is same for both film compositions*
- *In-plane epitaxy leads to six degenerate variants: variant boundaries*

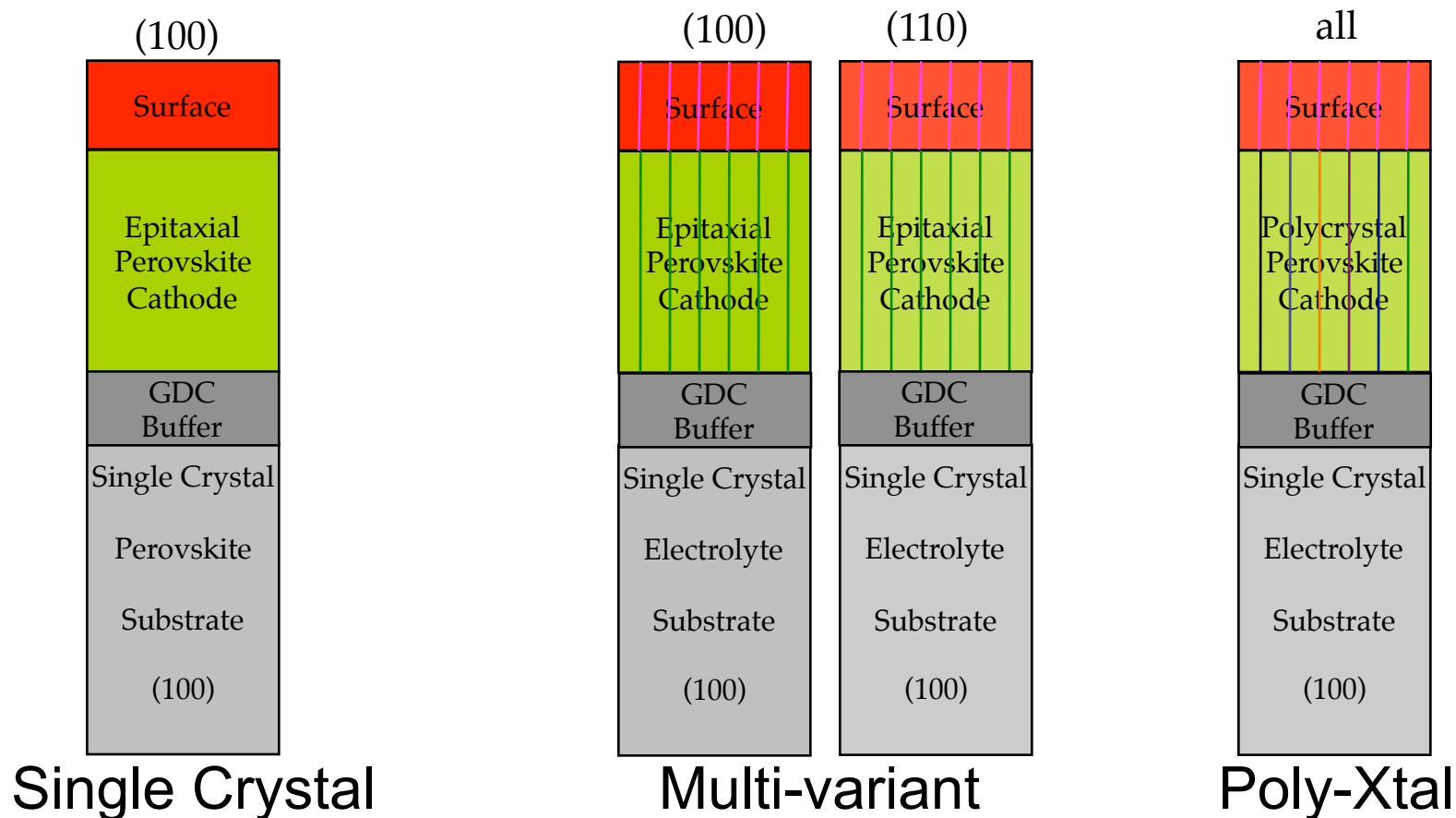
## AFM: 60 nm LSMO and LSCO on YSZ(111) *Surface Features are Unit-Cell Smooth*



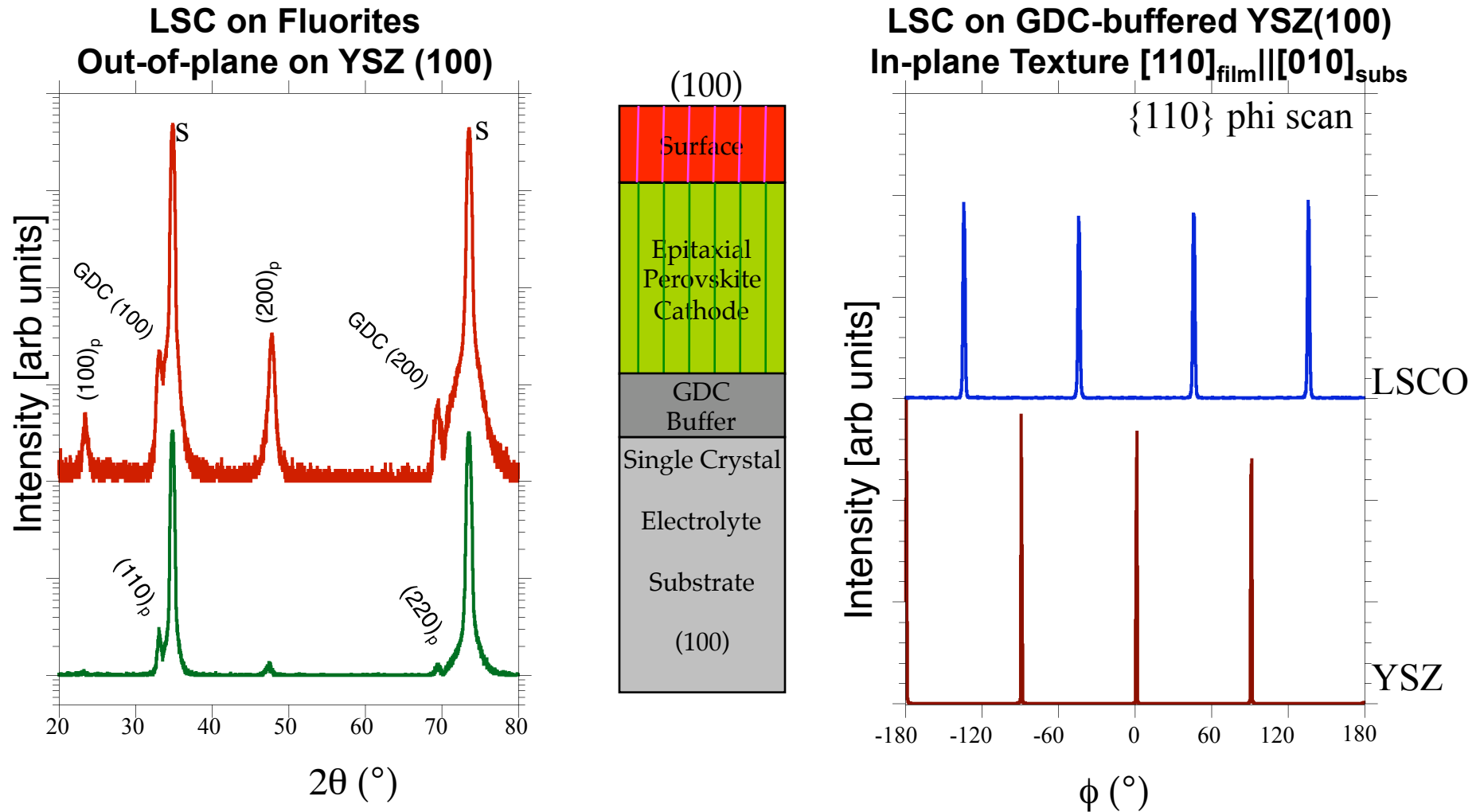
- *Surface Features are well defined*
  - *Films are unit-cell smooth*
  - *slight increase for LSCO roughness, but still unit-cell smooth*

# Can we attain Surface Engineered Samples on YSZ (100)?

Insert a Buffer Layer of GDC to Change Mismatch and Chemistry  
Useful Heterostructure for LSCF Measurements



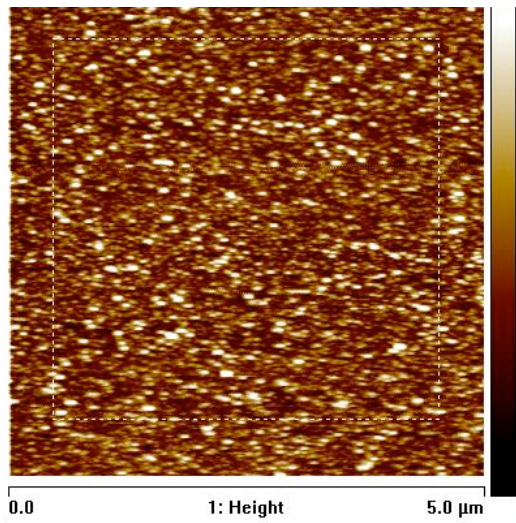
# XRD: 100 nm LSCO on YSZ(100) and GDC(50 nm)-YSZ(100) Epitaxy on 100-oriented electrolyte obtained



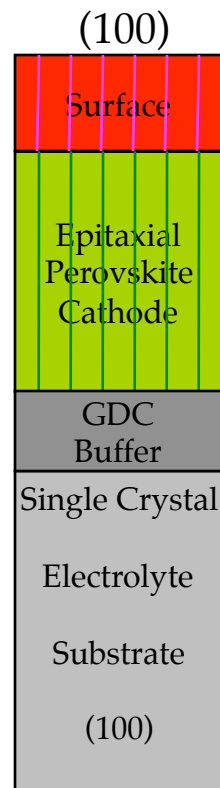
- *Perovskite - Fluorite (YSZ) (100) Epitaxy is found on GDC(100)*
- *In-plane epitaxy leads to four degenerate variants: variant boundaries*

# AFM: LSCO on YSZ(100) and GDC-Buffered YSZ(100) *Epitaxial Surface Features are Unit-Cell Smooth*

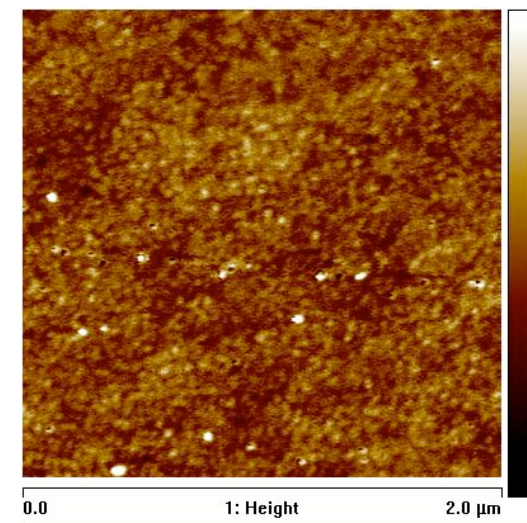
LSC on YSZ(100)



polycrystalline  
rms roughness = 6.0 Å



LSC on GDC-buffered YSZ(100)



Multivariant epitaxy  
rms roughness = 2.67 Å

- *Surface Features are well defined*
  - *Films are unit-cell smooth*
  - *Good decrease for epitaxial LSCO films*

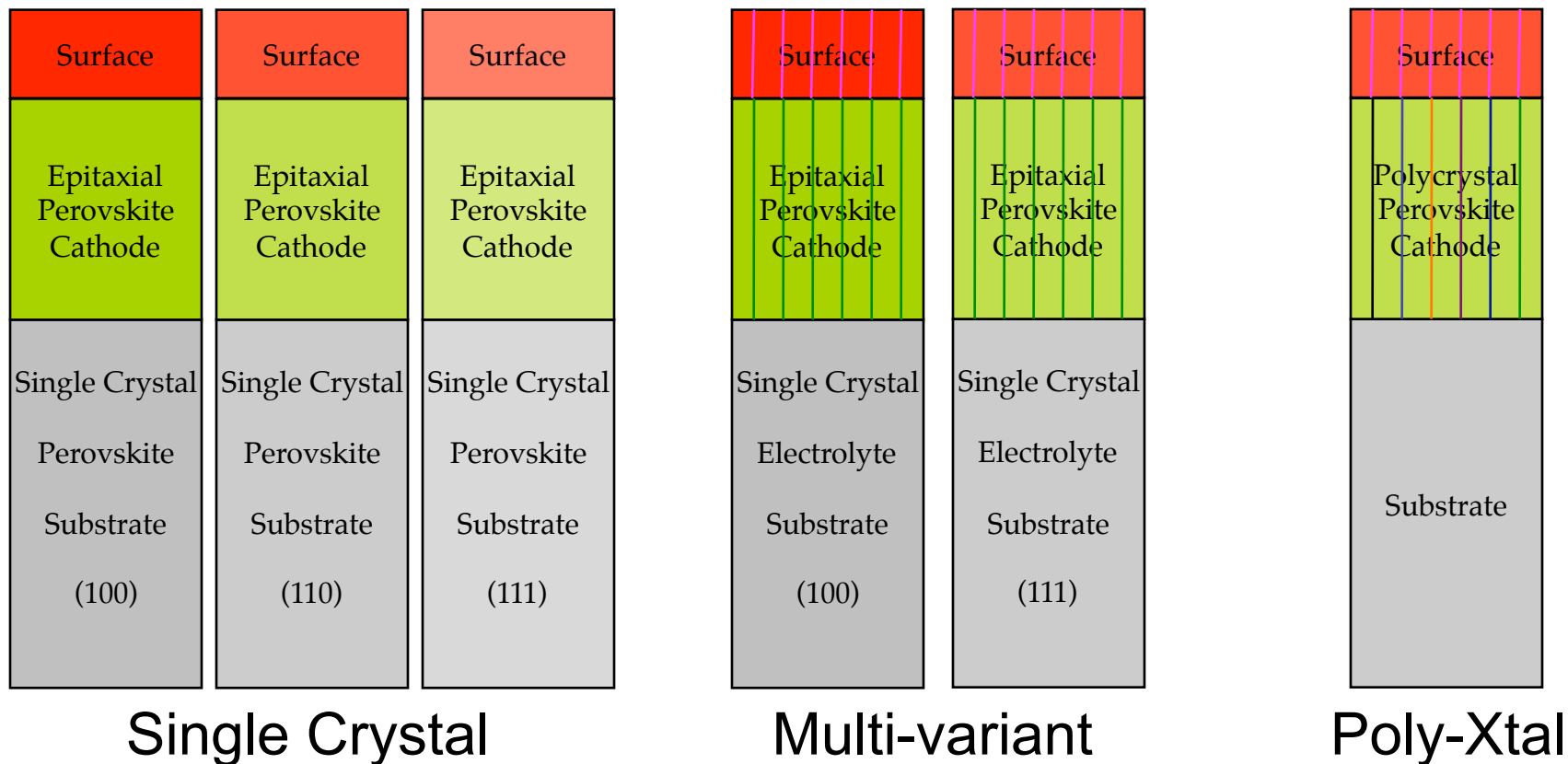


# Thin Film Samples Driving Surface Science

**Reaction Occurs at Surface:**



Films Allow for Surface / Microstructural Control

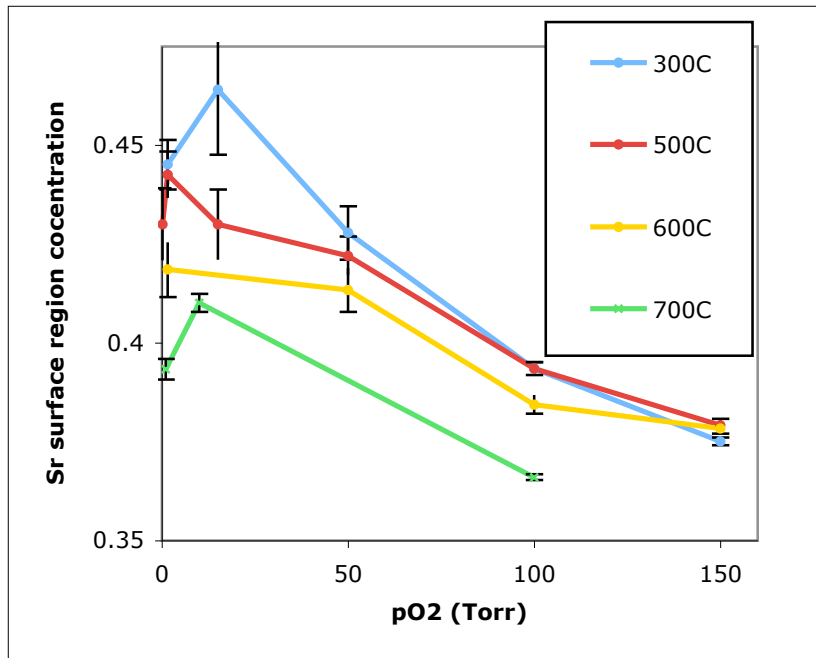


# Summary of Sample Preparation

- *Growth of High-Quality Thin Films*
  - *Perovskite / Perovskite Epitaxy and Surface Control Achieved*
    - *LSM and LSC (and LNO) deposited on many Perovskites*
    - *Cube-on-cube epitaxy on various orientations*
    - *Unit-cell roughness obtained*
  - *Perovskite / Fluorite Epitaxy and Surface Control Achieved*
    - *LSM and LSC (110)[111] epitaxy on YSZ (111)[[11-2]*
    - *LSM and LSC (100)[011]epitaxy on GDC-YSZ (100)[010]*
    - *Unit-cell roughness obtained*
    - *6 and 4 variants observed on (111) and (100) fluorites*
- *Samples Provided to Collaborators*
  - *Measured Surface Chemistry at APS*
  - *Measured Electronic Properties at MIT*

# Chemistry of (100) LSMO Surfaces

20 nm thickness  $\text{La}_{0.7}\text{Sr}_{0.3}\text{MnO}_3$



TXRF Spectra Show Sr-Enhancement

Not a function of Strain / Substrate

Is a function of T and Pressure  
Reversible

How does THIS effect properties?

Detailed Structure and Surface Segregation vs

Oxygen Activity

J. Eastman, D. Fong, P. Fuoss  
APS - ANL

Detailed Structure and Surface Segregation vs

Electrochemical Activity

K.-C. Chang, D. J. Myers, J. D. Carter, H. You  
APS-ANL

B. Yildiz, MIT

# Thickness Dependent Properties LSMO on Nb-Doped STO(100)

*Thin Layers are fully strained (XRD)*

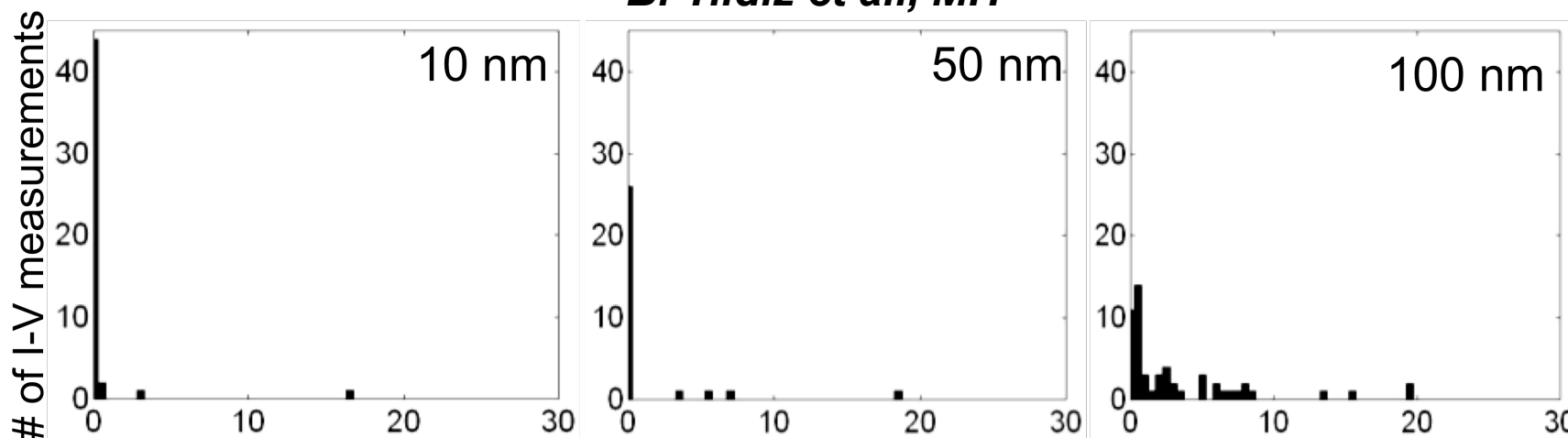
*Thin layers can relax by point defect formation*

*Films relax with thickness by dislocation formation*

*Interface with substrate can affect fermi level location*

## Scanning Tunneling Spectroscopy

*B. Yildiz et al., MIT*



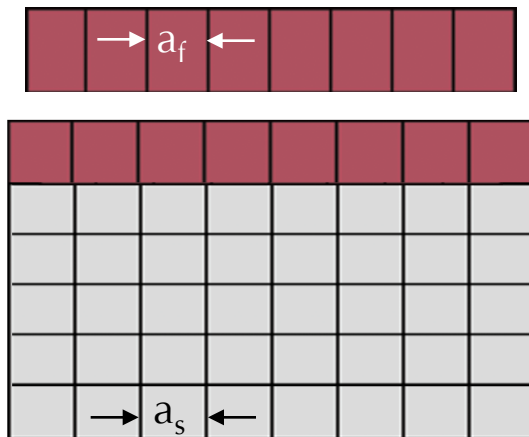
Fermi-level tunneling conductance (dl/dV @ 0 V, nA/V)

*Thinner LSM films have insulating surfaces  
with large band gap (1.5 – 2.2 V) at ambient conditions.*

# Cathode thin film growth – Substrate choice and orientation

## Mismatch Strain

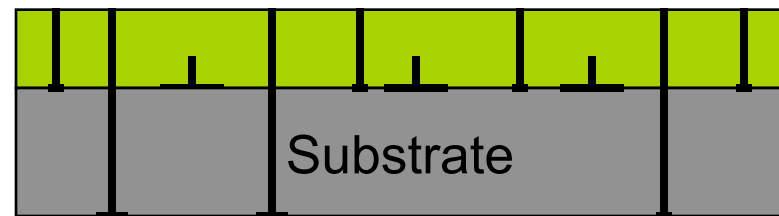
$$f = \frac{(a_s - a_f)}{a_f}$$



$$w_{strain}^{max} = \frac{2\mu(1+\nu)f^2}{(1-\nu)}$$

## Dislocations

Misfit  
Threading (relaxation)  
Threading (inherited)



*Substrates have different lattice mismatches and  
Different dislocation densities*

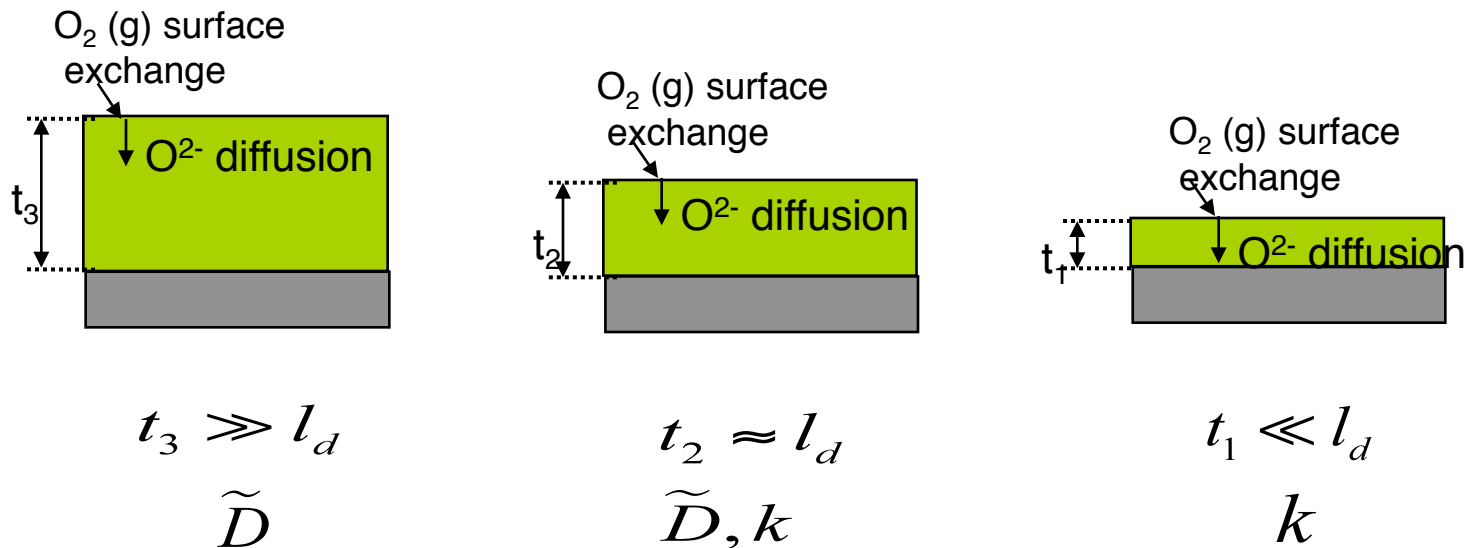
# ECR part: $\text{La}_{0.6}\text{Sr}_{0.4}\text{CoO}_3$ (50nm film) on YSZ (111)

## Background:

An abrupt change in oxygen pressure  $\longrightarrow \Delta C_{\text{O}_2}$  in MIEC.  
 Measuring  $\Delta\sigma_e$  can  $\longrightarrow$  monitor  $\Delta C_{\text{O}_2}$  in MIEC.  
 Analyzing the ECR data  $\longrightarrow$  get  $\tilde{D}$  and/or  $k$

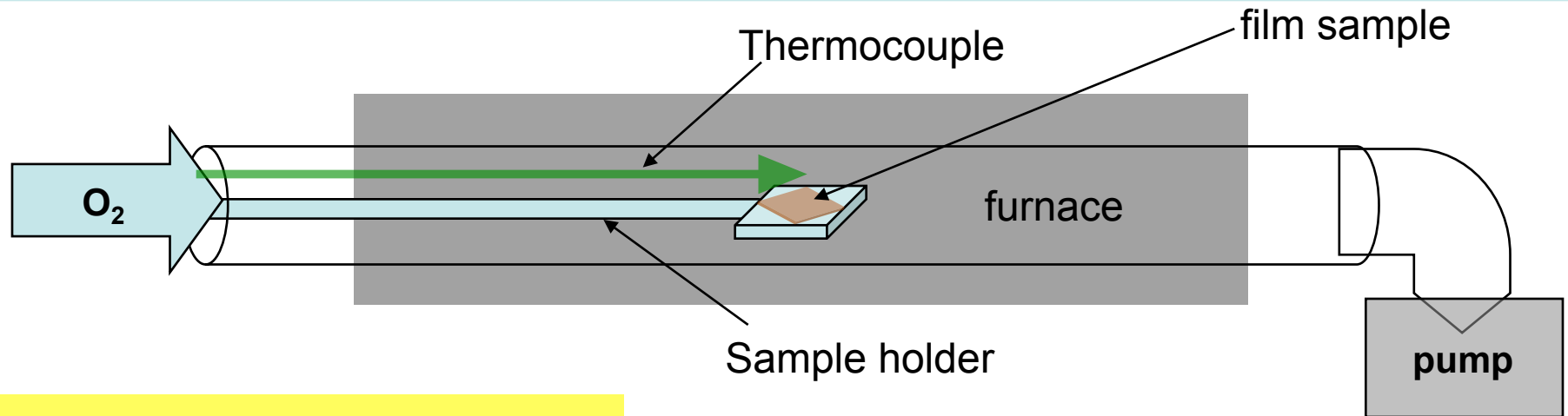
Characteristic length of the sample:  $l_d = \tilde{D}/k$

$\tilde{D}$  : chemical diffusion coefficient       $k$  : surface exchange coefficient

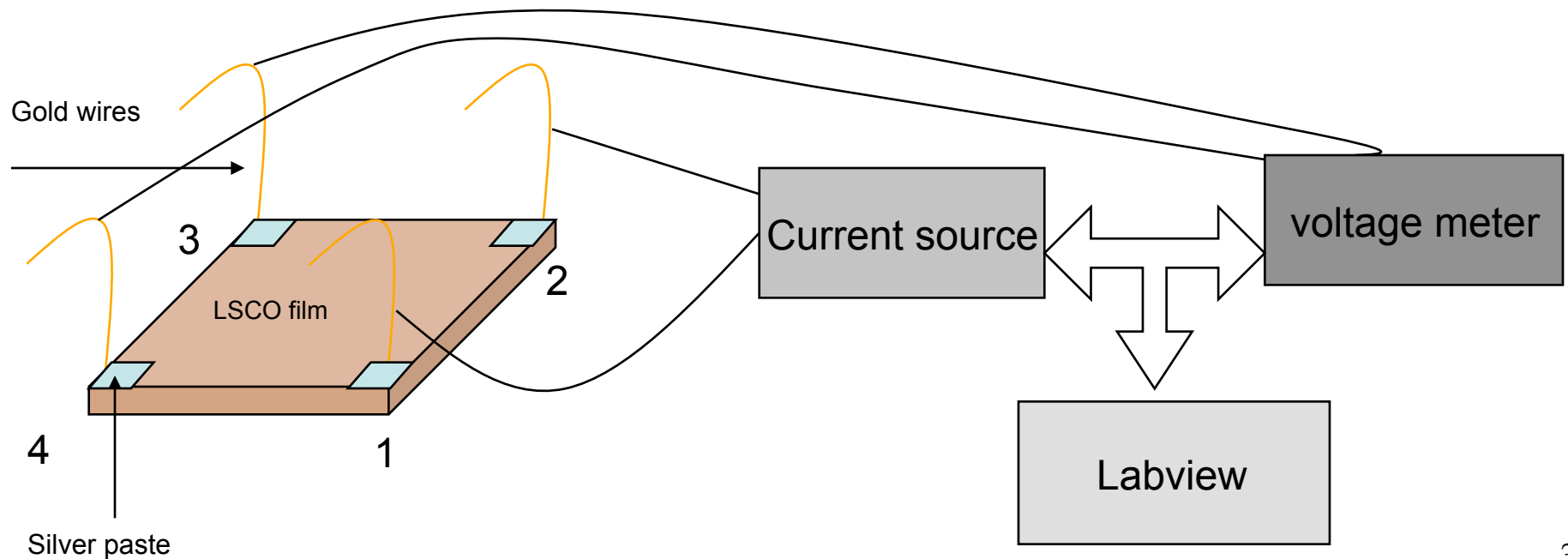




# Experimental Approach for ECR: Determine surface exchange constant $k_{chem}$



## Van der Pauw measurement:

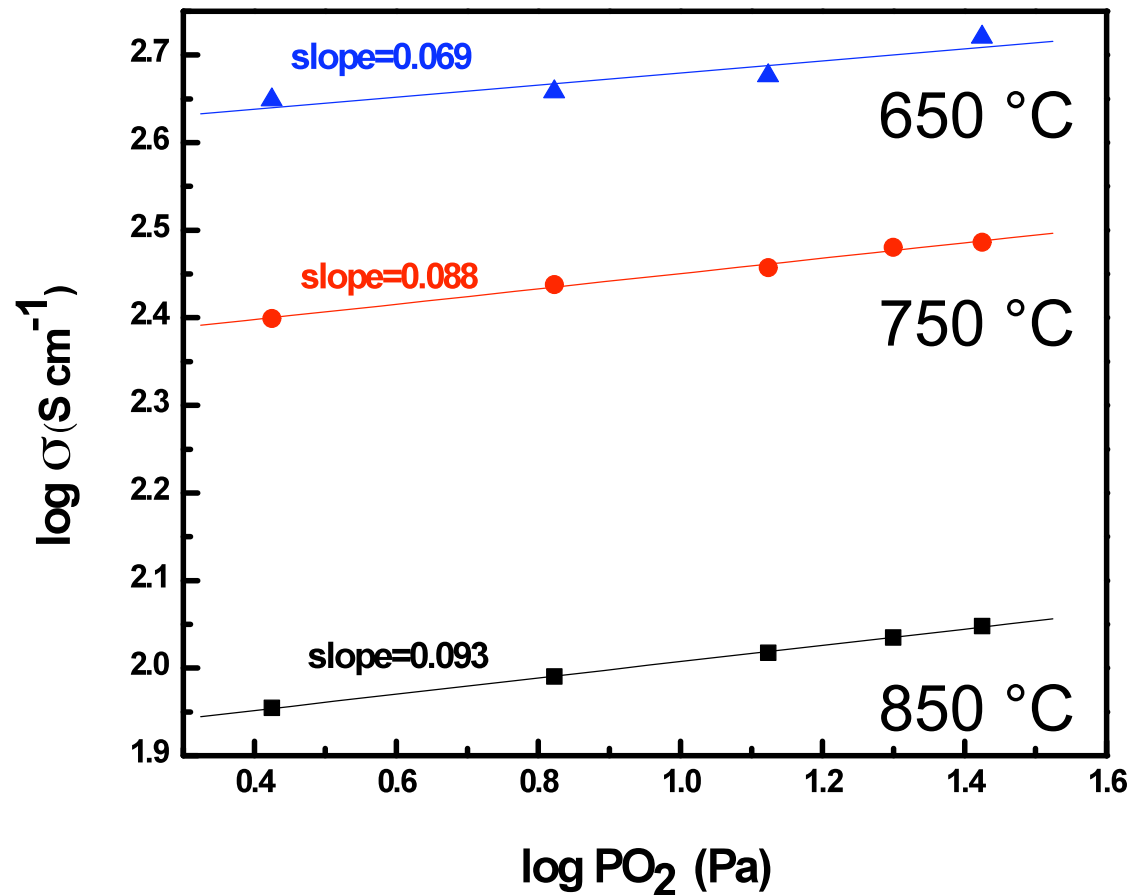
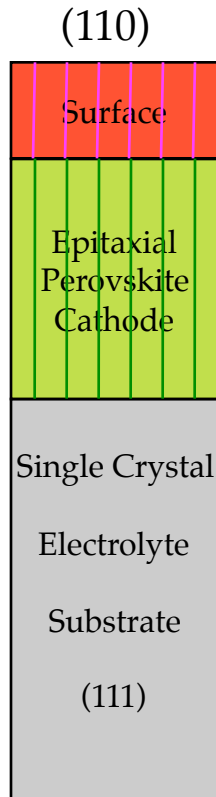


# 50 nm thick LSCO(110) on YSZ(111) Nanoparticle Infiltration Thickness

*Pressure Range Corresponds*

*reducing regions for cathodes ( $10^{-8}$  -  $10^{-4}$  atm)*

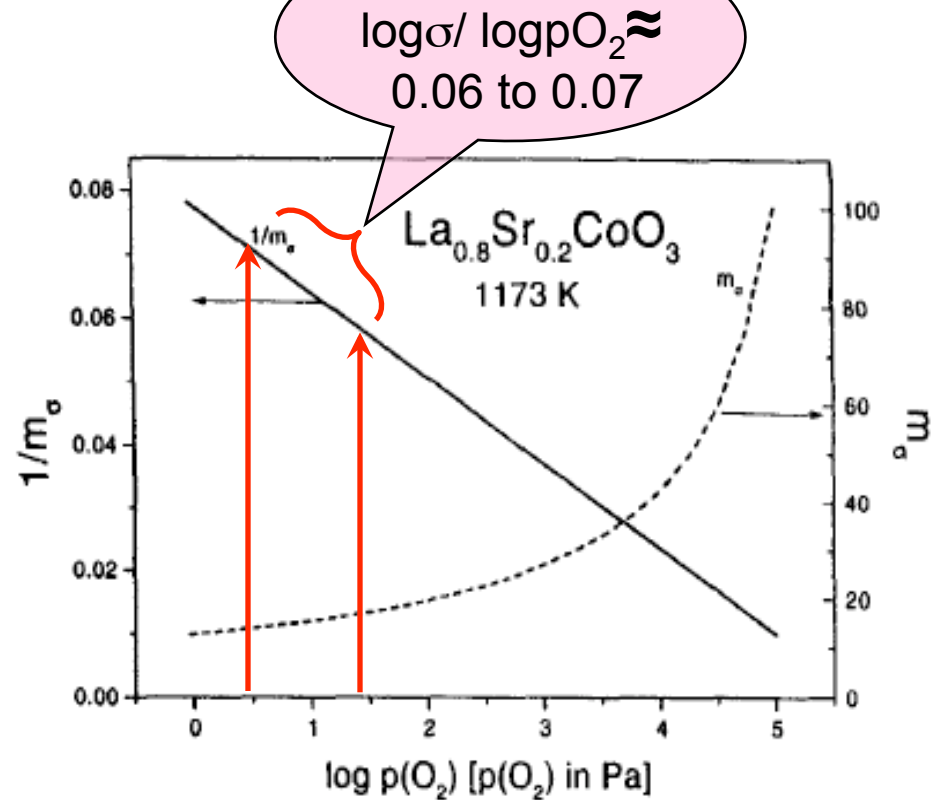
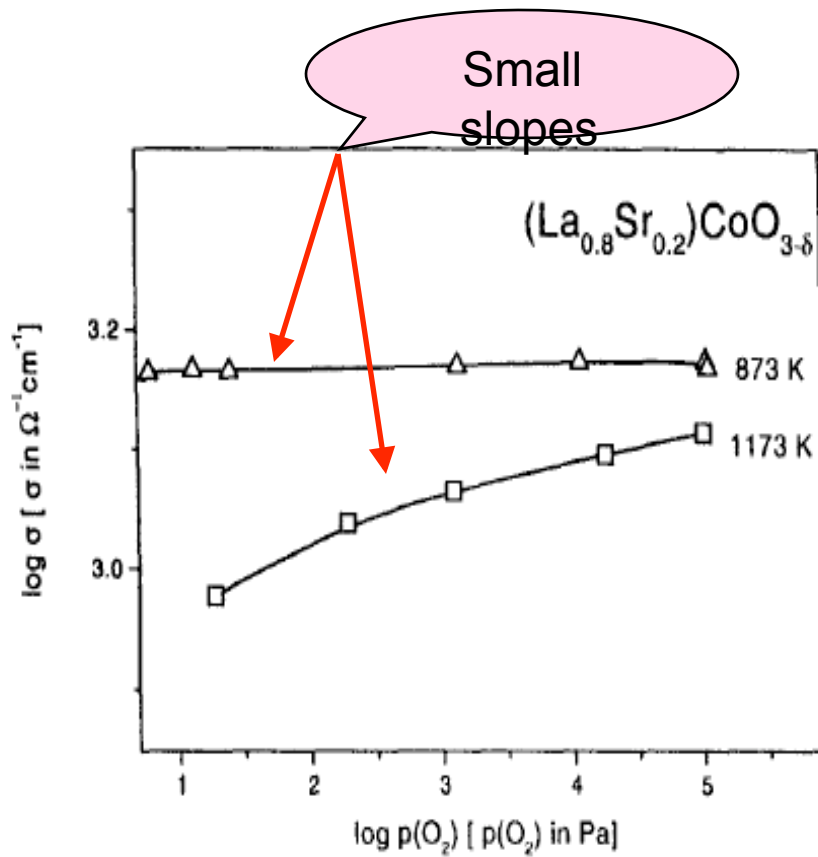
*film growth pressure ranges (.01 – 100 mTorr)*



*Steady State Values Provide a Reality Check and Allow us to Explore Bulk Changes*

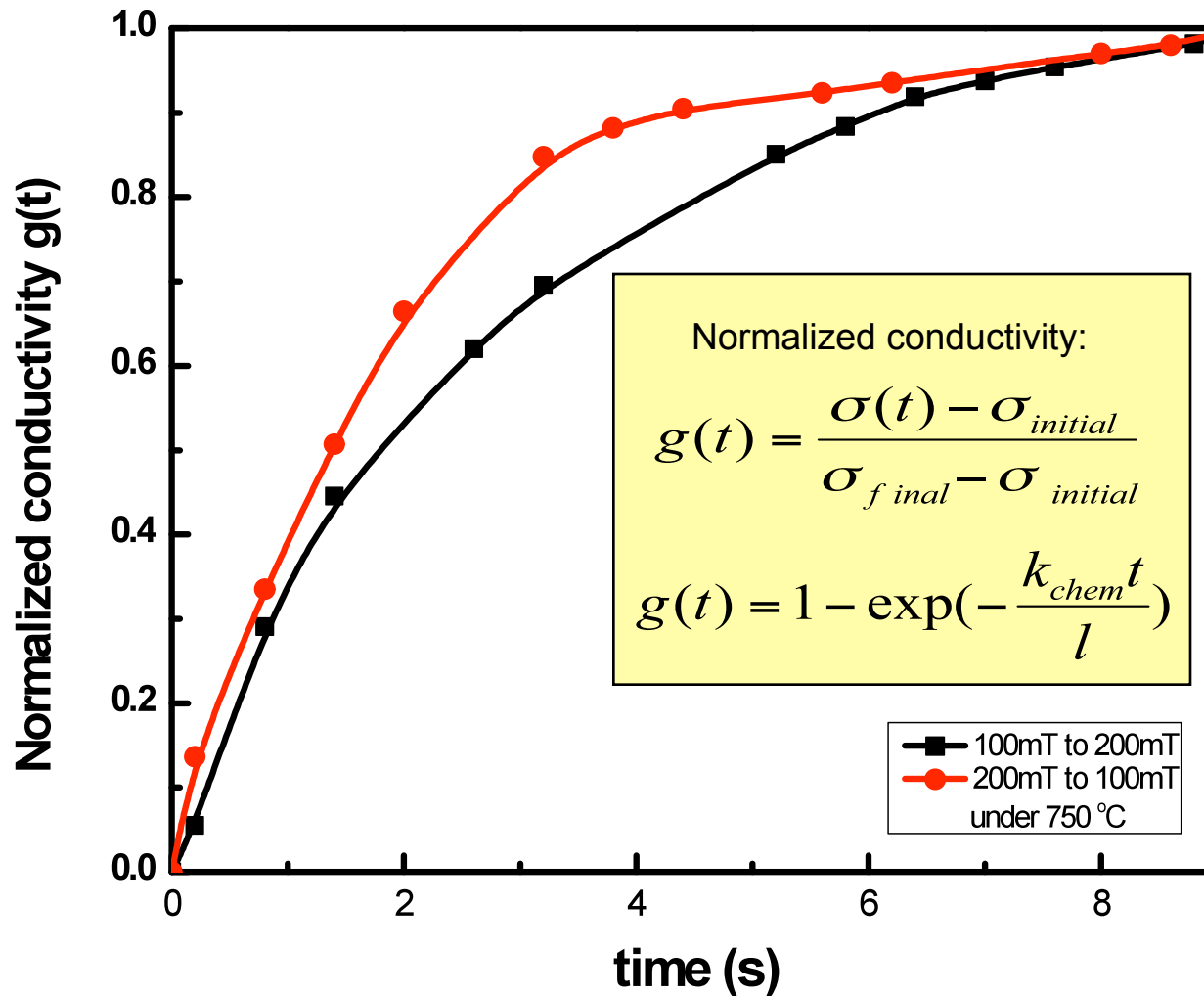
# LSCO electrical properties

## Agree with Literature Observations



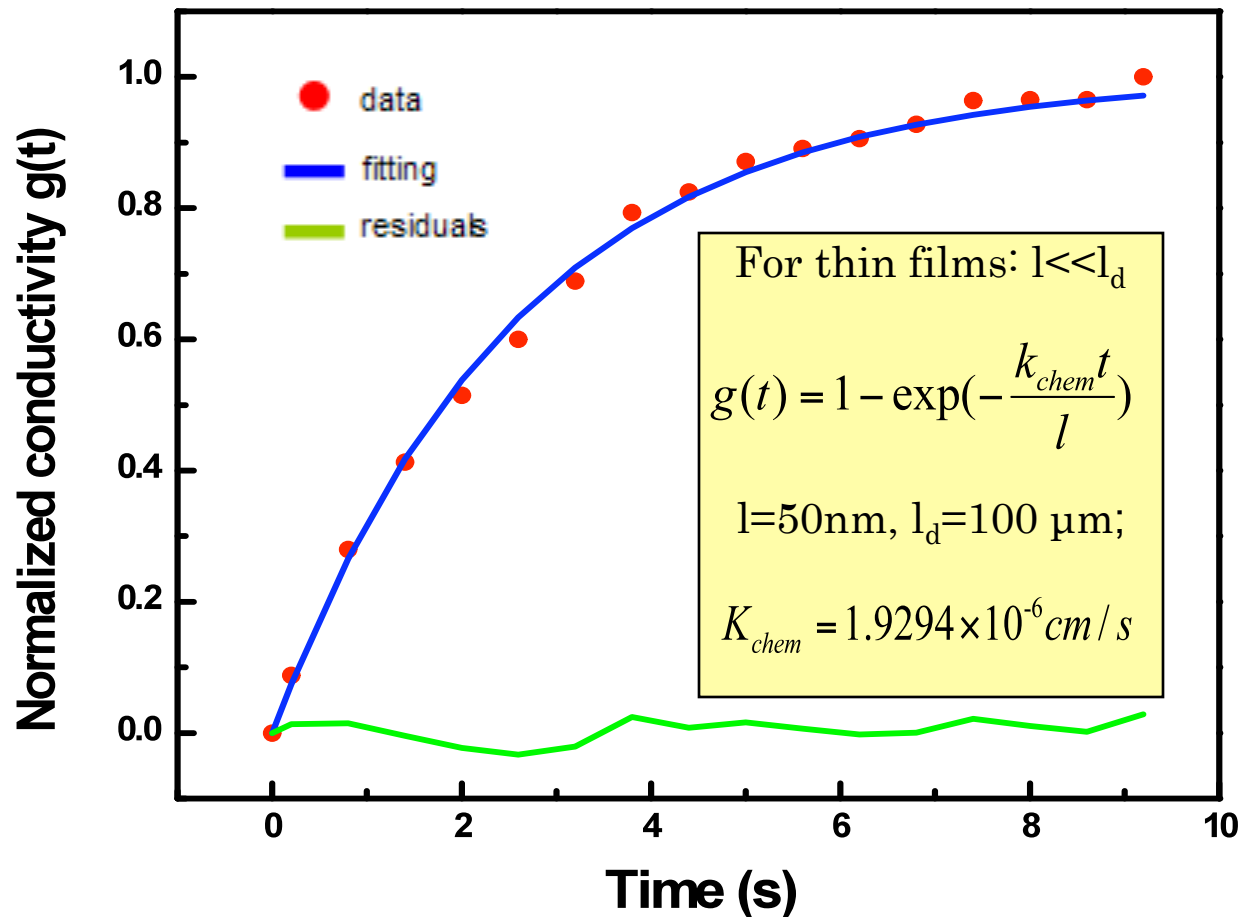
*Bak et al., Ionics 7 (2001) 388;*  
*Mizusaki et al., J. Electrochem. Soc., 136 (1989) 2082.*

# ECR Measurement (50nm) $\text{La}_{0.6}\text{Sr}_{0.4}\text{CoO}_3$ (110) / YSZ (111)



- *ECR can be measured using the vacuum arrangement*
- *Resistivity values are similar to those reported in literature*

## ECR Fitting / $k_{chem}$ determination (50nm) $La_{0.6}Sr_{0.4}CoO_3$ (110) / YSZ (111)



- *Data fits reasonably well to a single exponent*
- *Values are similar to those observed in literature (on different type samples)*
- *High-throughput / basic surface science experiments can be designed*

## Comparison to Literature

	This study	Chen <i>et al.</i> *
Film composition	<div style="border: 1px solid black; padding: 2px; display: inline-block;">Epitaxial Perovskite Cathode</div> $\text{La}_{0.6}\text{Sr}_{0.4}\text{CoO}_3$	<div style="border: 1px solid black; padding: 2px; display: inline-block;">Epitaxial Perovskite Cathode</div> $\text{La}_{0.5}\text{Sr}_{0.5}\text{CoO}_3$
Substrate	YSZ(111) (LSC 110)	LaAlO <sub>3</sub> (100) (LSC 100)
Pressure range	Low 100 to 200mTorr	High 380 to 760Torr
$K_{\text{chem}}$ at 650°C	$1 - 4 \times 10^{-6} \text{ cm/s}$	$\approx 1 \times 10^{-6} \text{ cm/s}$

\* X.Chen *et al.*/Solid State Ionics 146(2002)405-413

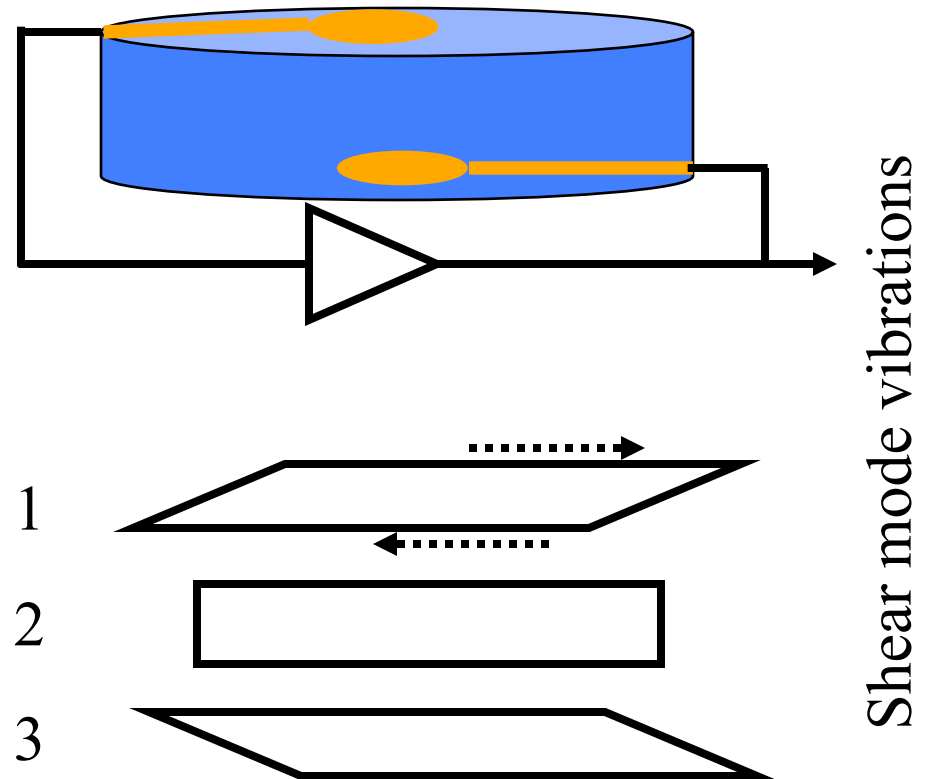
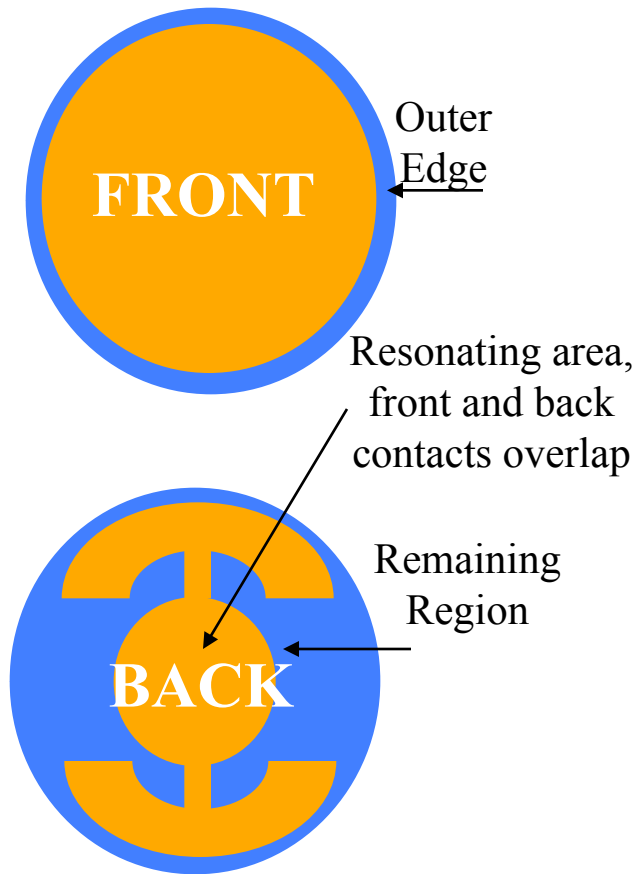
*How are microstructural / surface differences reflected in ECR?*



# Summary of ECR Measurements

- *High vacuum compatible experimental set-up completed*
  - *Pressure can be changed from 0.01 mTorr to 100 mTorr for ECR*
  - *Van der Pauw or linear 4-probe possible*
- *Measurements at 650°C agree with order of magnitude in literature*
  - *(110)LSC films on (111)YSZ*
  - $k_{chem} = 2-8 \times 10^{-6} \text{ cm/s}$
  - *some differences with respect to trends for values at final P*
- *Future*
  - *Measure different temperature / pressure ranges*
  - *Measure LSC on perovskites / GDC-YSZ(100)*
  - *Measure surface modified samples*
  - *Combine with other work to generate understanding of surface*

# High-T Piezoelectric Crystal Microbalances



$\text{GaPO}_4$

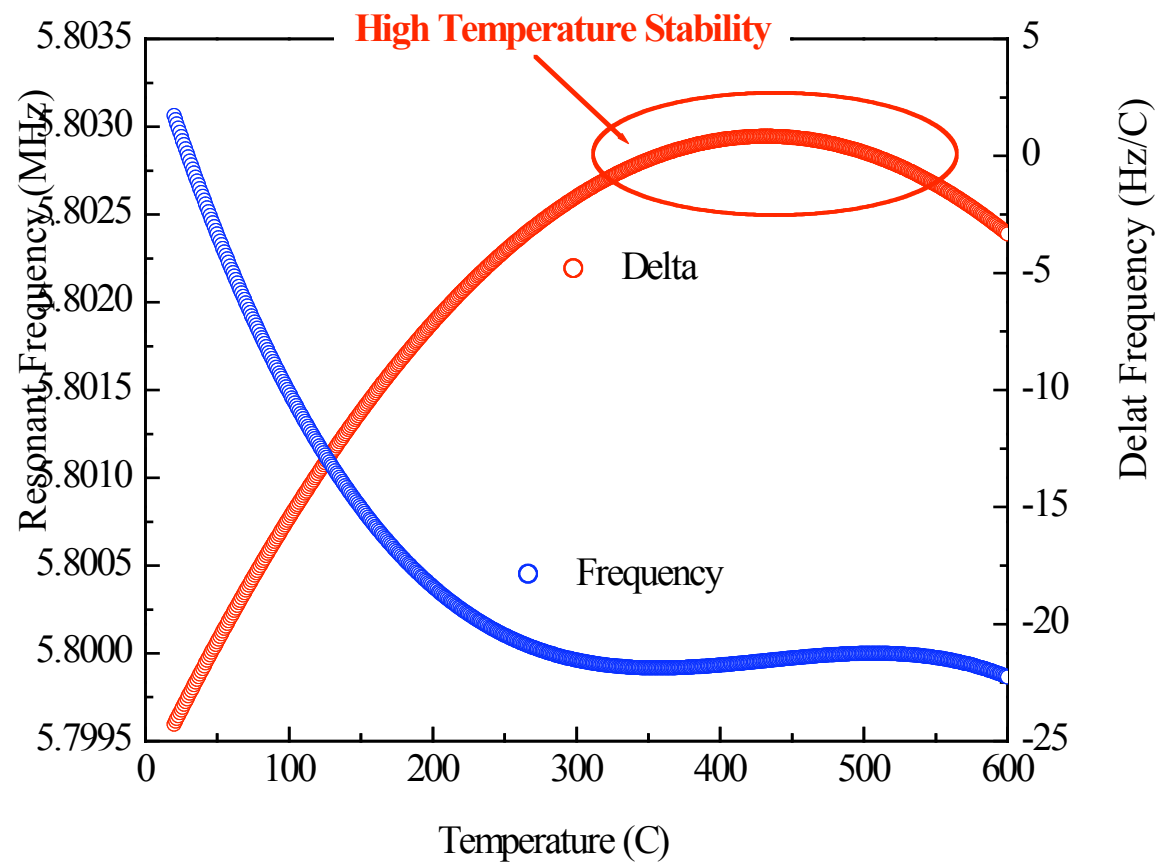
**Diameter = 0.55 inch; Thickness = 0.2 mm;**

**$F_0 = 5.8 \text{ MHz}$ , Sensitivity +/- 3 Hz**

# *GaPO<sub>4</sub> Piezoelectric Crystal Microbalances*

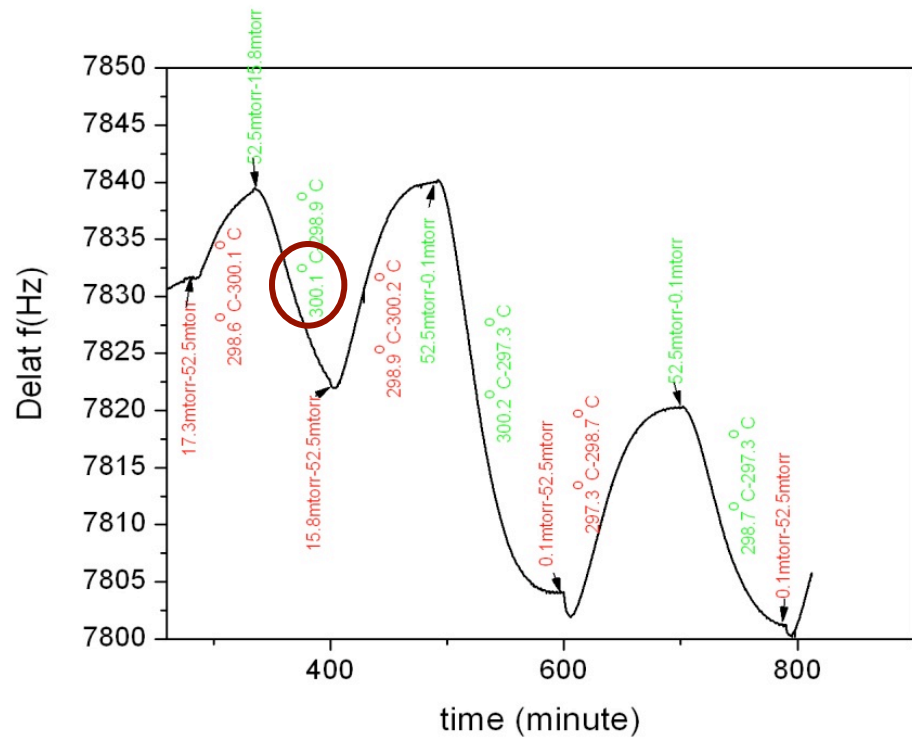
GaPO<sub>4</sub> is Piezoelectric until > 900°C

Has good temperature stability of Frequency



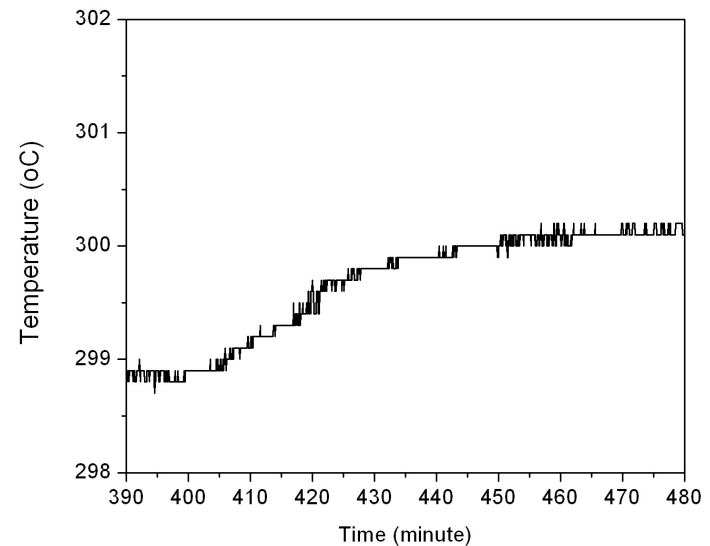
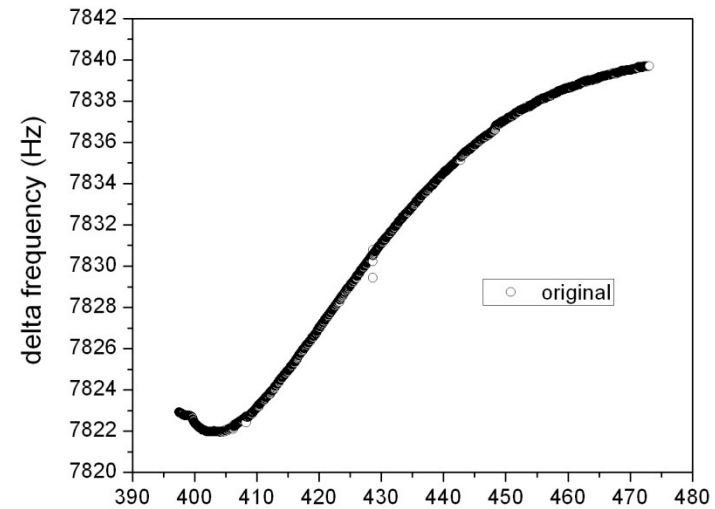
# Analyzing PCM Data at 300 °C

## LaNiO<sub>3</sub>/PCM-300°C



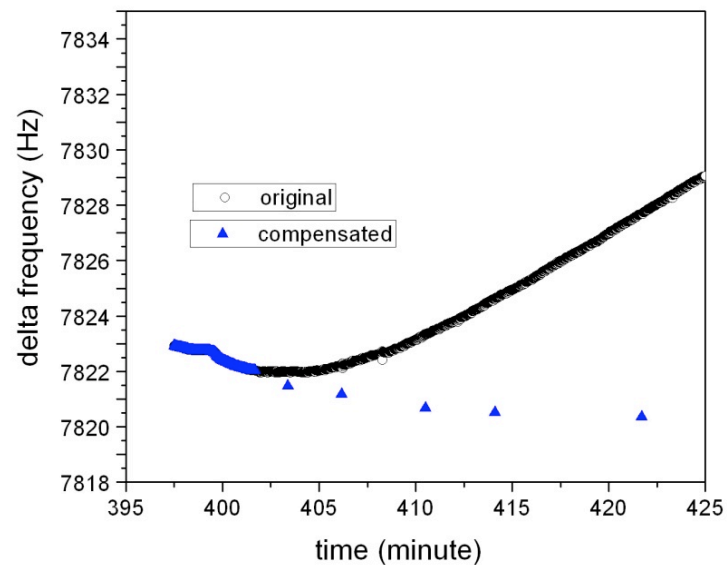
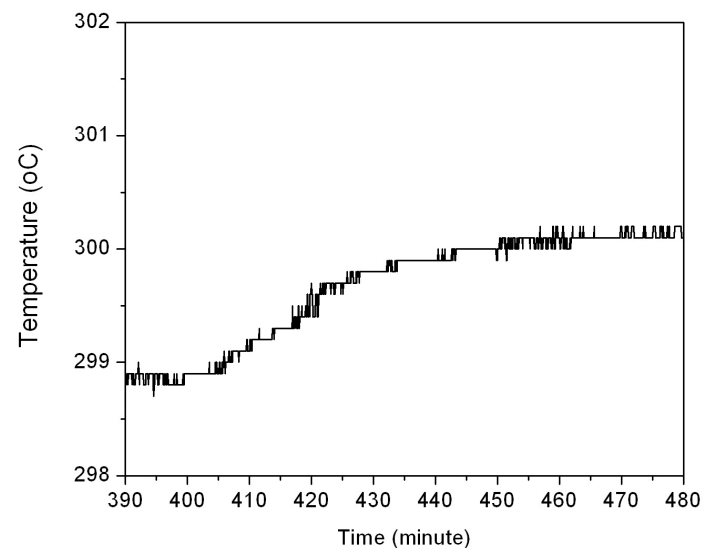
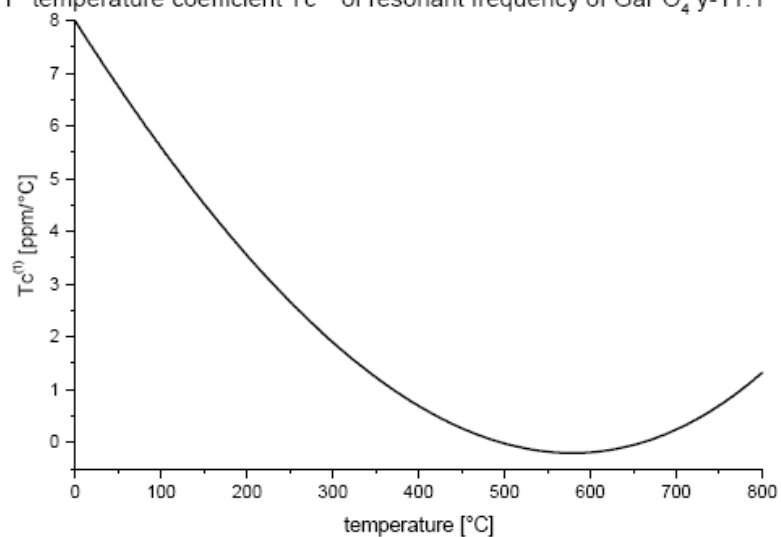
- Part of the frequency change is caused by temperature change

## 15 to 50 mTorr

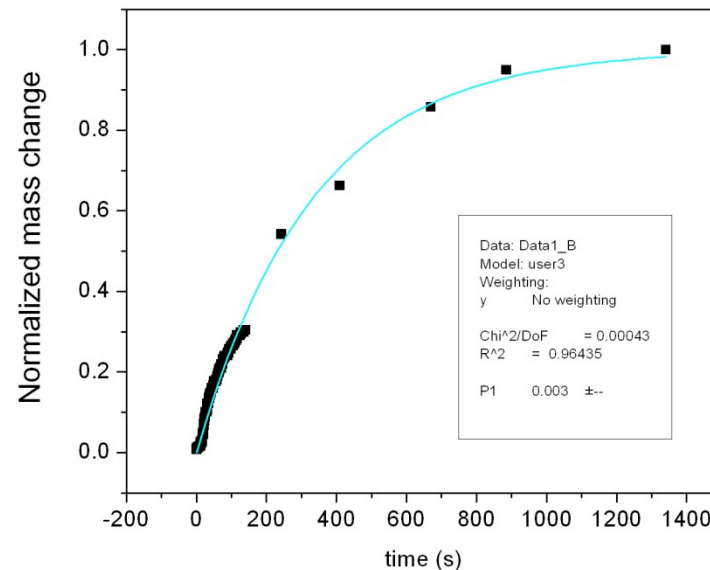


# Deconvoluting Temperature and Mass Change at 300 °C for LNO Films

1<sup>st</sup> temperature coefficient  $T_c^{(1)}$  of resonant frequency of  $\text{GaPO}_4$   $y$ -11.1° cut



# Transient Measurements to Determine Surface Properties

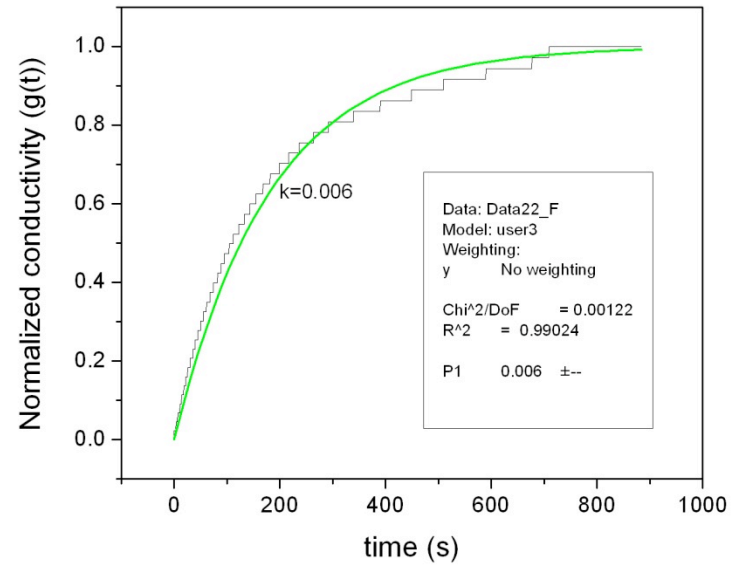
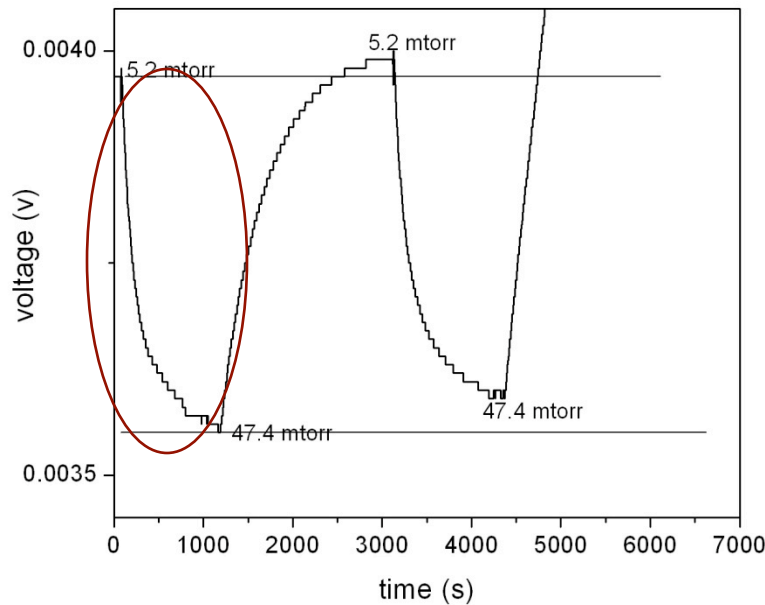


Fitting equation  
 $y = 1 - \exp(-A*t)$   
 $A = 0.003$

- for thin film where  $k_{chem} = A * l_{film} = 0.003 \times 130nm = 3.9 \times 10^{-8} \text{ cm/s}$
- Need to focus on extracting  
adsorption step from dissociation step



# ECR-LaNiO<sub>3</sub>/YSZ(100)-350°C



- for thin film where  $k_{chem} = A \cdot l_{film} = 0.006 \times 130\text{nm} = 7.8 \times 10^{-8} \text{ cm/s}$
- This  $k_{chem}$  is in the same range as measured with PCM

➤  $k_{chem}$  for  $\text{La}_2\text{NiO}_{4+x}$  ceramics at this temperature is  $7 \times 10^{-7} \text{ cm/s}$   
(G .Kim et al Solid State Ionics 177(2006))

# PCM Measurements

- *Piezoelectric Crystal Microbalances*
  - *Good intermediate temperature stability*
  - *LaNiO<sub>3</sub> films on GaPO<sub>4</sub> measured at 350°C*
  - *$k_{chem}$  is reasonable but no good literature comparison*
  - *LaNiO<sub>3</sub> films on ultrathin SrTiO<sub>3</sub> crystals measured on GaPO<sub>4</sub> PCMs*
- *Future*
  - *LaNiO<sub>3</sub> films on ultrathin SrTiO<sub>3</sub> crystals measured on GaPO<sub>4</sub> PCMs*
  - *Temperature dependent measurements*
  - *High-temperature holder (collaboration with company)*
  - *Measure LSM-LSC-LSF surface properties*

# Summary

- ***Providing Samples to Large-Scale Effort to Understand / Engineer Cathodes Surfaces for Improved Performance***
- ***Effort focused on Thin Film / Engineered Surfaces***
  - Generate three classes of films with engineered microstructure / surface*
  - Epitaxial Single Crystal (100), (110), (111)*
  - Epitaxial Multi-variant (100), (110)*
  - Polycrystalline*
- ***Initial Measurements to combine conductivity / mass / electronic structure***
  - ECR (110) LSCO has  $k_{chem}$  on in the range of  $2-8 \times 10^{-6}$  cm at  $650^{\circ}\text{C}$*   
 *$k_{chem}$  affected by final pressure and oxidation/reduction*
  - STS thin (strained) epitaxial LSM on STO layers are insulating*  
*thick (relaxed) epitaxial LSM on STO layers are conducting*
  - PCM Can use polycrystalline films or Epitaxial film/substrate*  
*Temperature compensation is essential*  
*LNO has  $k_{chem}$  on the order of  $4-8 \times 10^{-8}$  cm between  $300-350$*

# Future Directions

- ***Growth of High-Quality Thin Film Samples***
  - ***Perovskite / Perovskite Epitaxy and Surface Control***
  - ***Perovskite / Fluorite Epitaxy and Surface Control***
  - *Generation of Surface-Modified Samples*
- ***Surface Kinetics for Oxygen Uptake***
  - ***Electrical Conductivity Relaxation***
  - ***Piezoelectric Crystal Microbalance Gravimetry***
  - *Kelvin Probe Spectroscopy*
- ***Surface Thermodynamics of Oxygen Uptake***
  - ***Piezoelectric Crystal Microbalance Gravimetry***
  - *Kelvin Probe Spectroscopy*
- ***Electronic Structure***
  - *Kelvin Probe Spectroscopy*
  - *STM (MIT)*
- ***Ex-situ Surface Characterization for Correlations***
  - *Scanning Auger / XPS*

## *Acknowledgements*

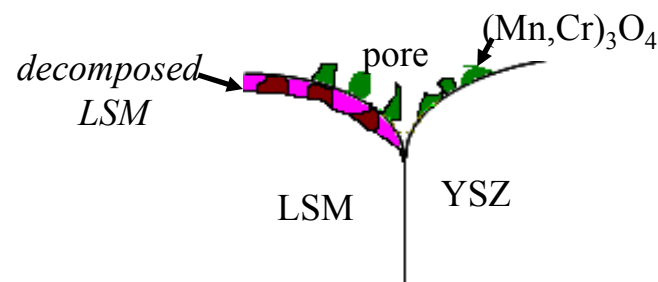
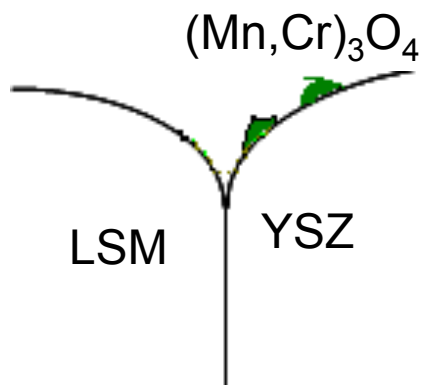
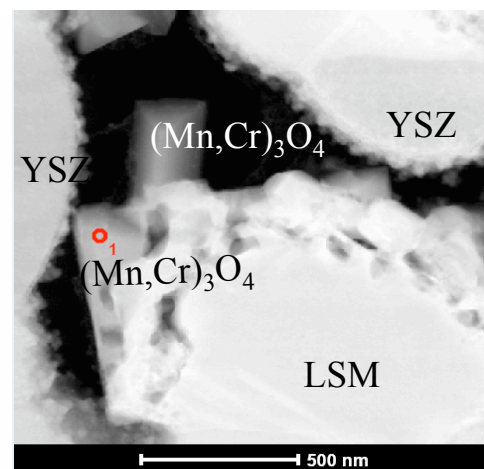
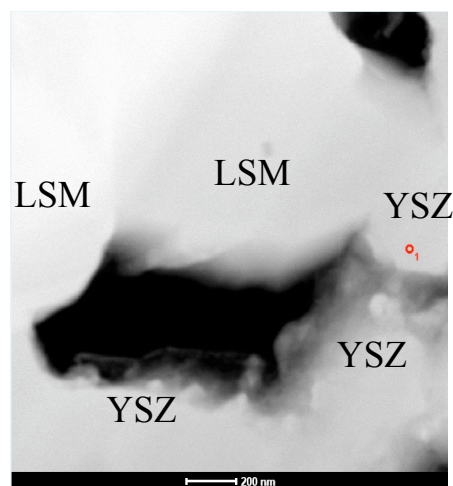
- SECA Program
  - Briggs White and Wayne Surdoval
- RDS – NETL

# Transmission Electron Microscopy

Argonne National Lab – Carnegie Mellon – SECA

Delphi – Carnegie Mellon – SECA

## Local Microstructural / Chemical / Phase Information



*T. A. Cruse, B. J. Ingram, M. Krumpelt, S. Wang, and P. A. Salvador, in "TMS 2008 Annual Meeting Supplemental Proceedings Volume 1: Materials Processing and Properties," pp. 571-580 (2008).*

## Investigate Degradation of Cells

## Overarching Goals

*Put together a team of researchers to carry out*

*Surface Science on SOFC Cathode Materials*

*Generate in-situ / ex-situ correlations*

*Generate a complete description of surfaces / oxygen interaction*

*Identify the surface sensitive parameter that dictates overall cathode performance:*

*surface stoichiometry and orientation,*

*electronic character,*

*work function,*

*cation-gas bonding,*

*vacancy population, etc...*

## Objectives

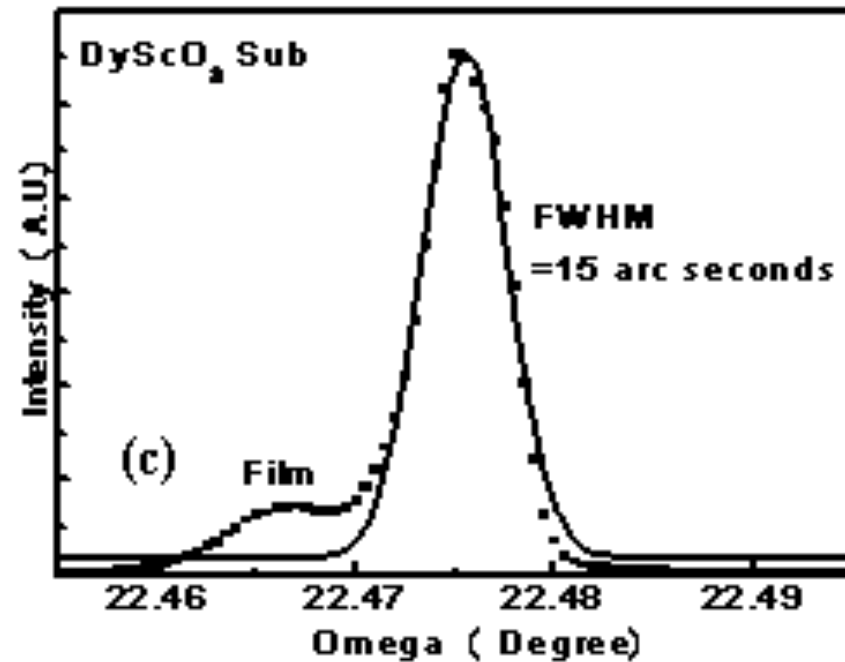
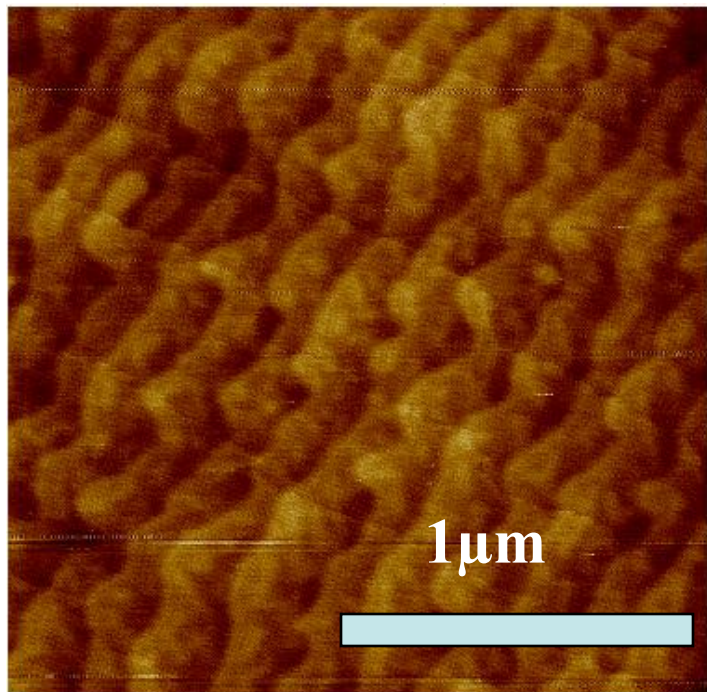
*(1) generate well-defined epitaxial, textured, and polycrystalline films having controlled surface chemistries*

*(2) generate experimental data on surface properties that indicate how the electrocatalytic activity of SOFC cathodes can be optimized to yield improved cathodes.*



# DyScO<sub>3</sub> Crystals

*Ultra-high Quality Perovskite Crystals*  
*Ultra high Quality Surfaces*  
*No Overlapping Elements with Films*  
*Highly Insulating (Good for ECR / PCM)*

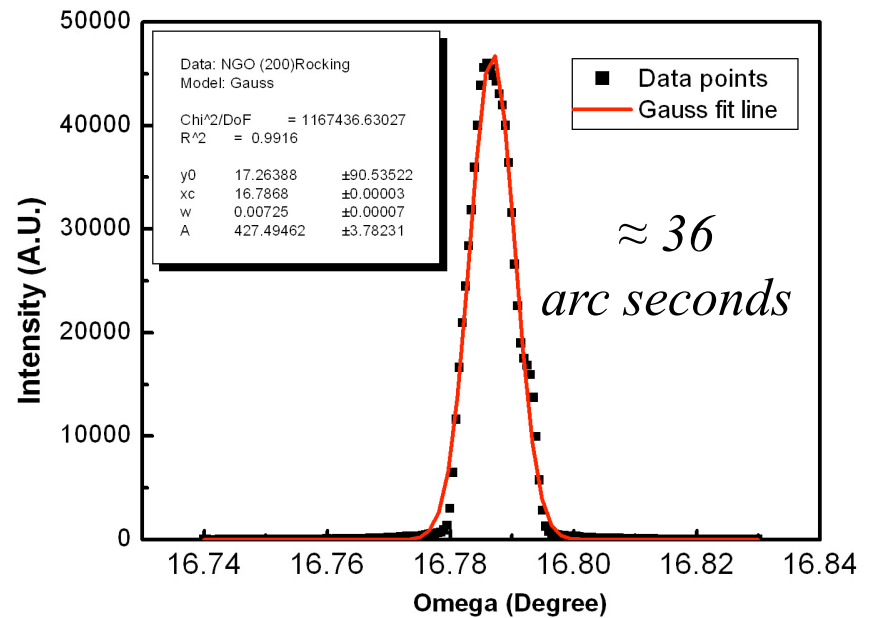
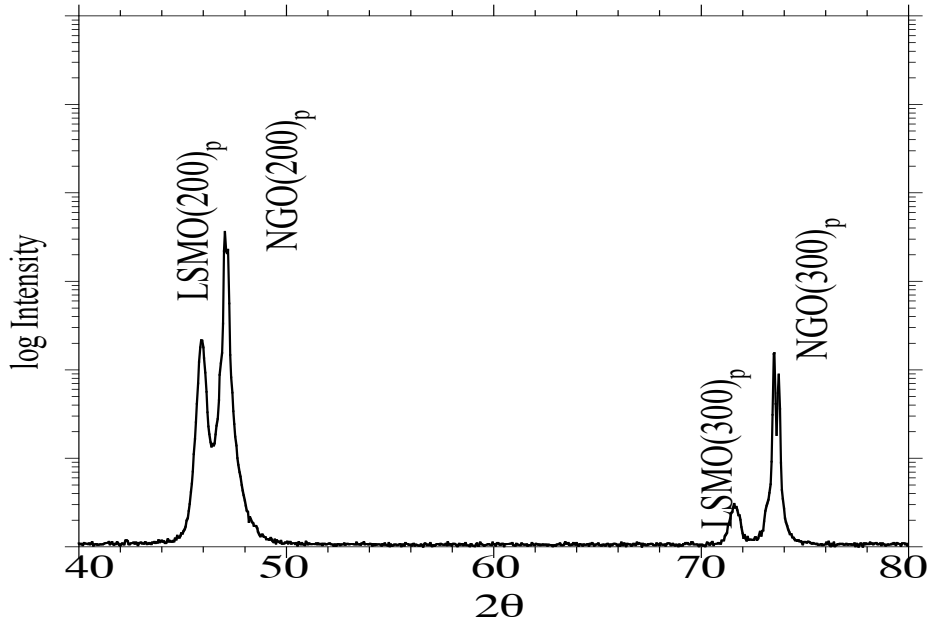


*Investigated Surface Chemistry at ANL using these Substrates*

# *(La,Sr)MnO<sub>3</sub> thin films on NdGaO<sub>3</sub>*

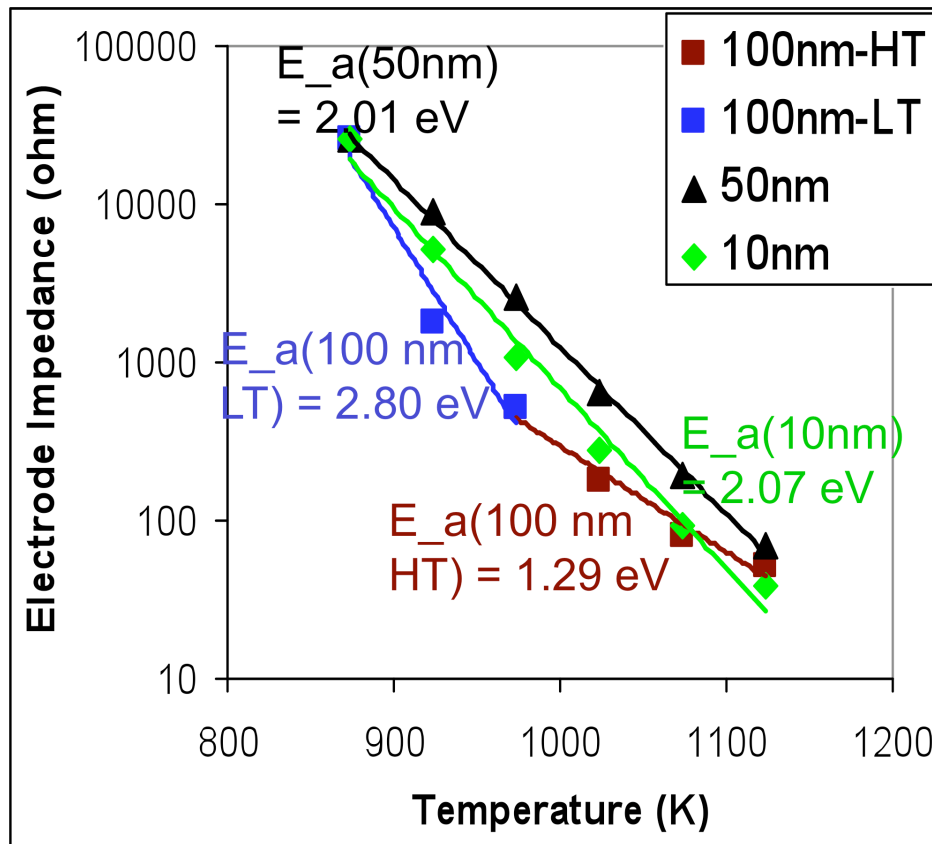
*Very-high Quality Perovskite Crystals  
No Overlapping Elements with Films  
Highly Insulating (Good for ECR / PCM)*

*La<sub>0.7</sub>Sr<sub>0.3</sub>MnO<sub>3</sub> (54 nm) deposited on NdGaO<sub>3</sub>(100)<sub>P</sub>*



*Need Reasonable Perovskite Electrolyte(s) for Electrochemistry*

# Impedance vs Thickness and Temperature



**2eV of effective activation energy indicates surface-limited oxygen reduction [1,2]**

**HT region for 100nm thick film indicates a change in the mechanism**

**Surface Limited Mechanism is Consistent with Fermi Level Conduction Mechanism**

[1] E. P. Murray, T. Tsai, S. A. Barnett, *Solid State Ionics* **110**, 235 (1998).

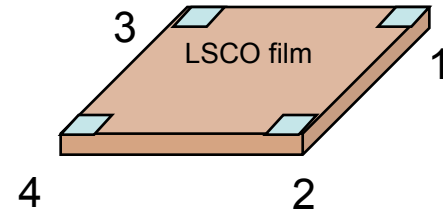
[2] S. P. Jiang, J. G. Love, Y. Ramprakash, *J. Power Sources* **110**, 201 (2002).

**Electronic Structure and Impedance are Correlated**

# Van der Pauw measurements

## Verifying that the Set-up works / Verifying the FILM uniformity

Let current = 1μA, then test on the film sample, we get:



V34	I12	0.272592 mv
V34	- I12	-0.272245 mv
V34	I21	-0.272351 mv
V34	-I21	0.272439 mv
V12	I34	0.271918 mv
V12	-I34	-0.272635 mv
V12	I43	-0.272340 mv
V12	-I43	0.272138 mv
V13	I42	-0.276759 mv
V13	-I42	0.271322 mv
V13	I24	0.270765 mv
V13	-I24	-0.274452 mv
V31	I42	0.272788 mv
V31	-I42	-0.27231 mv
V31	I24	-0.274130 mv
V31	-I24	0.272271 mv
V14	I32	0.00mv
V32	I41	0.00mv

Measure on edges :

1,2: current; 3,4: voltage  
Or  
2,3: current; 1,4: voltage  
Or  
3,4: current; 2,1: voltage  
Or  
4,1: current; 3,2: voltage

**Gives almost the same  
resistance value:  $R=V/I$   
with errors <1%**

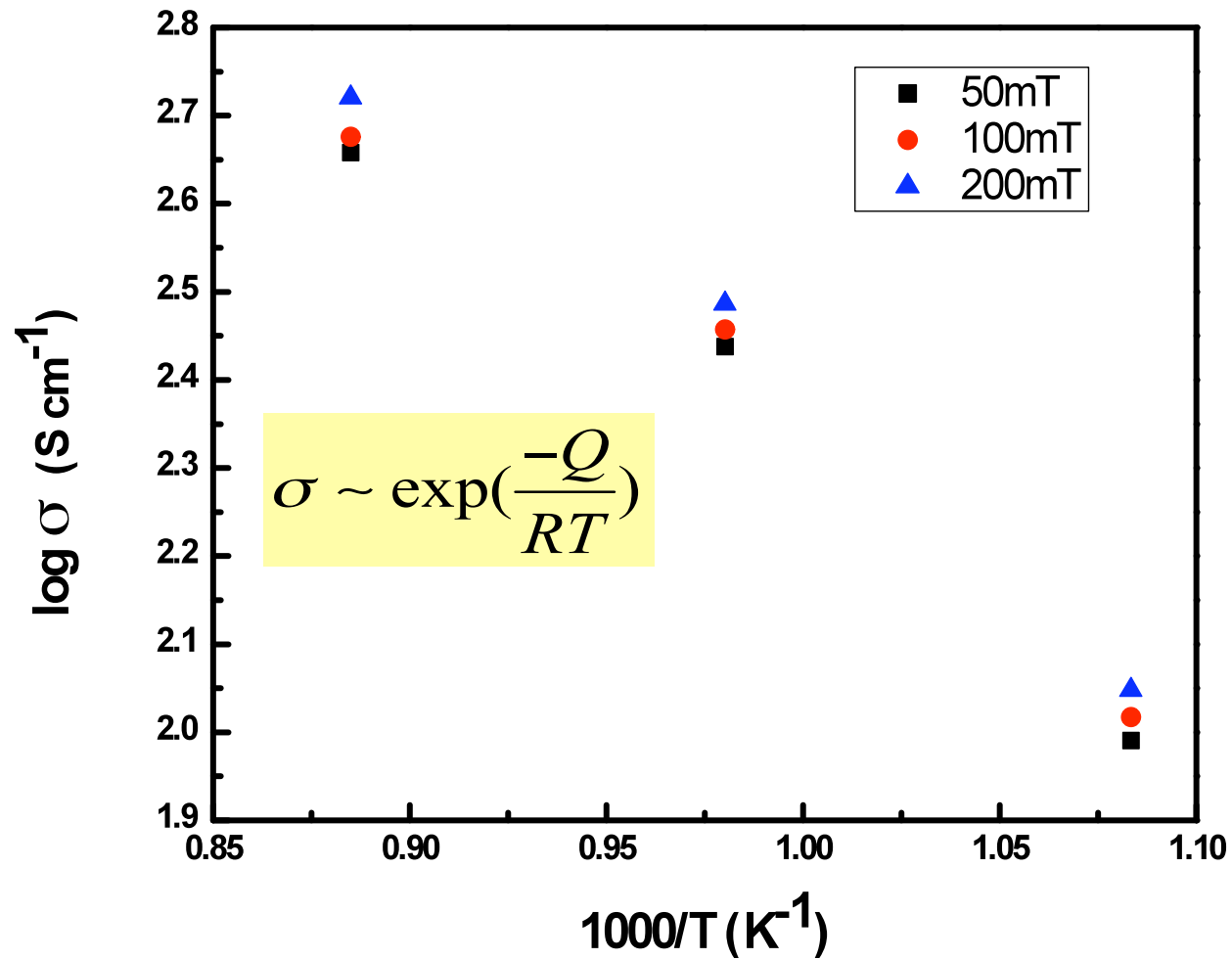
Measure on  
diagonals:

1,3: current; 2,4:  
voltage  
Or  
2,4: current; 1,3:  
voltage

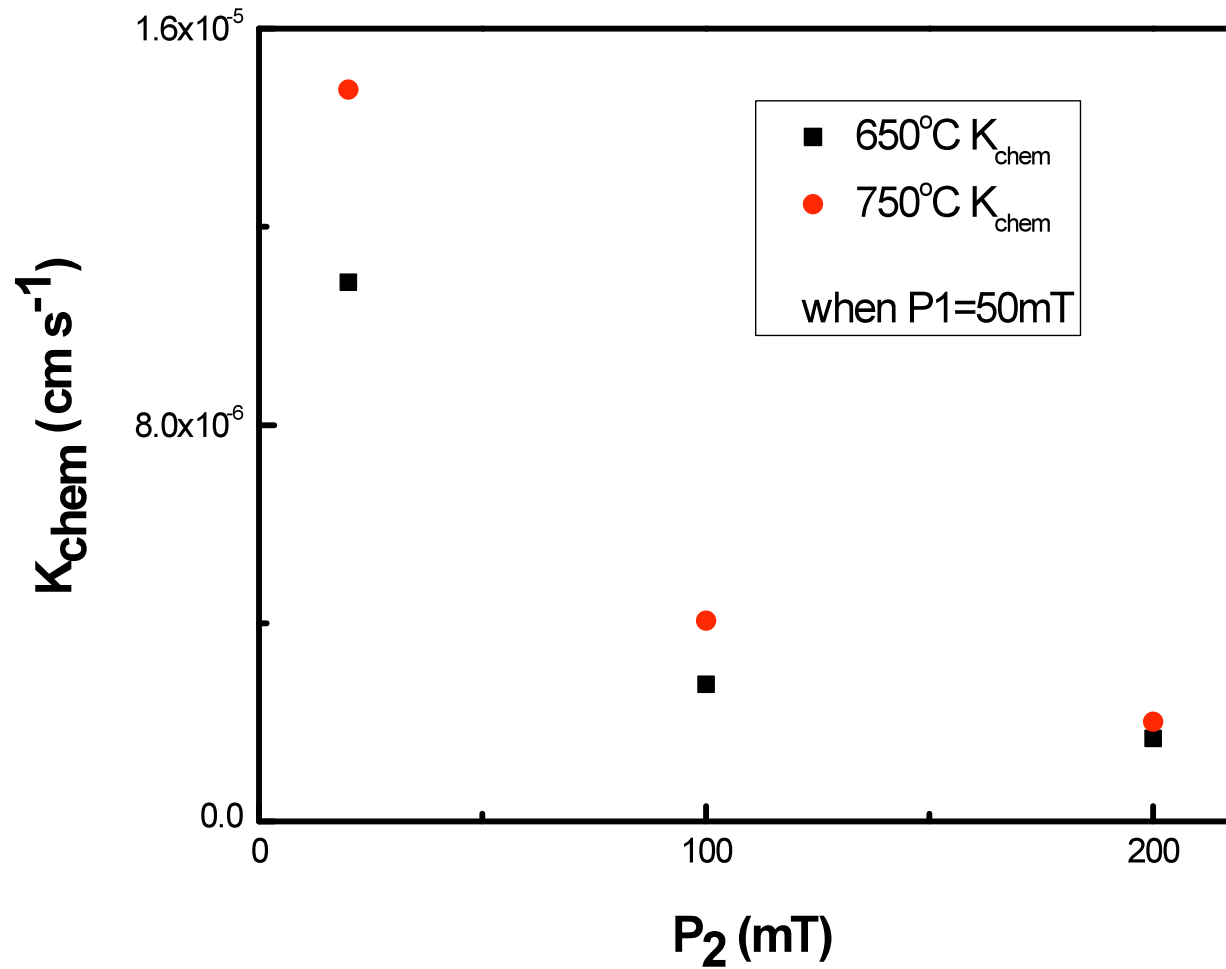
**gives  $R=0$**

**Thus, it is reasonable to do VDP  
measurement without switching.**

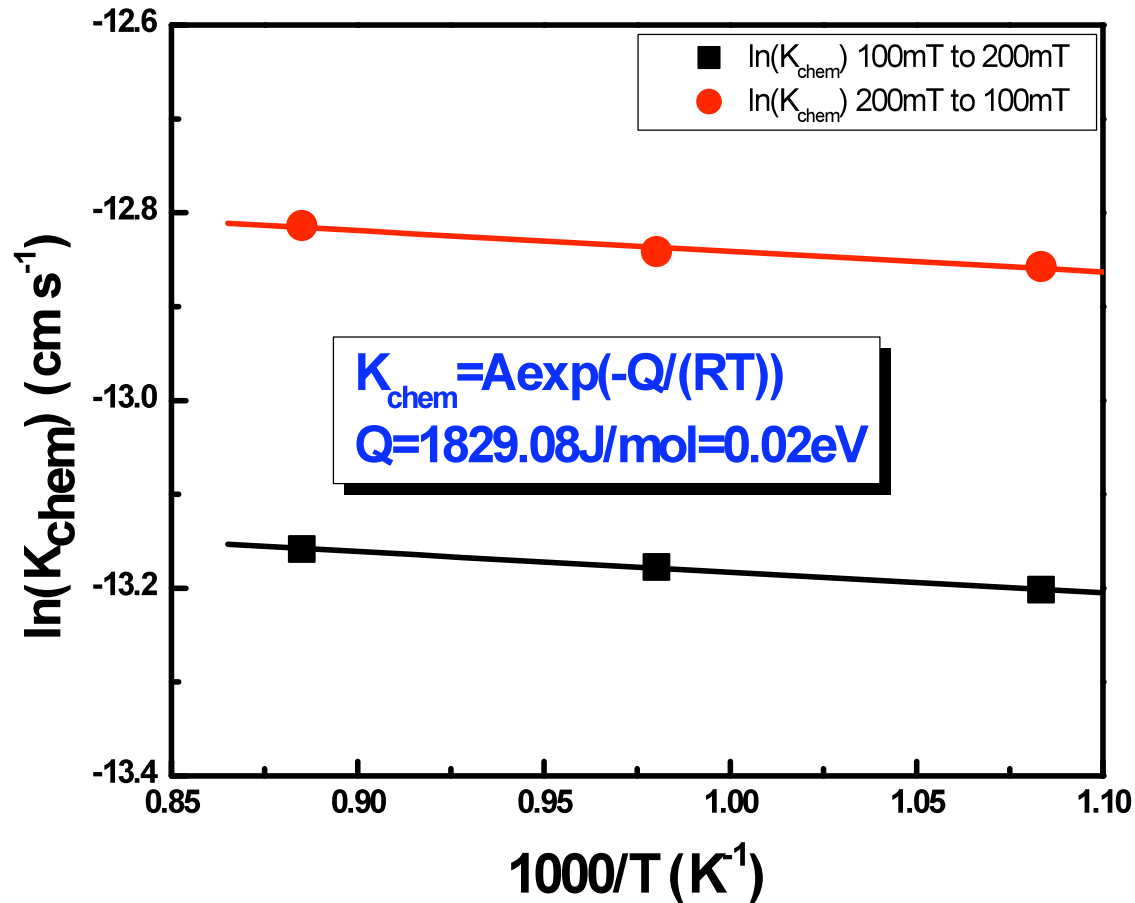
## LSCO conductivity change with temperature



# $K_{chem}$ dependency on final oxygen pressure



# Activation energy (Q) determination



650°C  $K_{chem} = 1.85 \times 10^{-6}$  (100→200mTorr)  
 $K_{chem} = 2.61 \times 10^{-6}$  (200→100mTorr)

50nm LSCO(110) on YSZ(111)

in this study

650°C  $K_{chem} = 0.92 \times 10^{-6}$  (380Torr>760Torr)  
 $K_{chem} = 0.84 \times 10^{-6}$  (760Torr>380Torr)

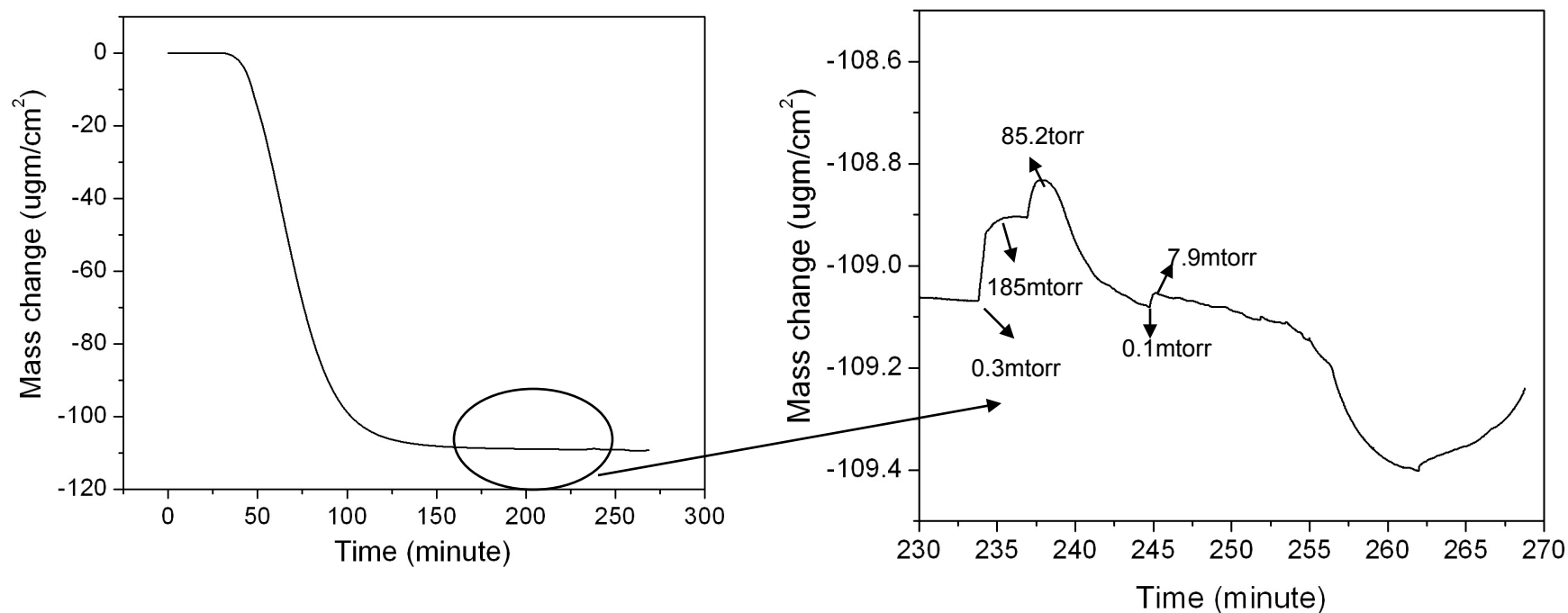
500nm LSCO (100) on LAO(100)

\* X.Chen *et al.*/Solid State Ionics 146(2002)405-413



# Mass Changes on Pressure Changes

## QCM is Sensitive to Mass Changes

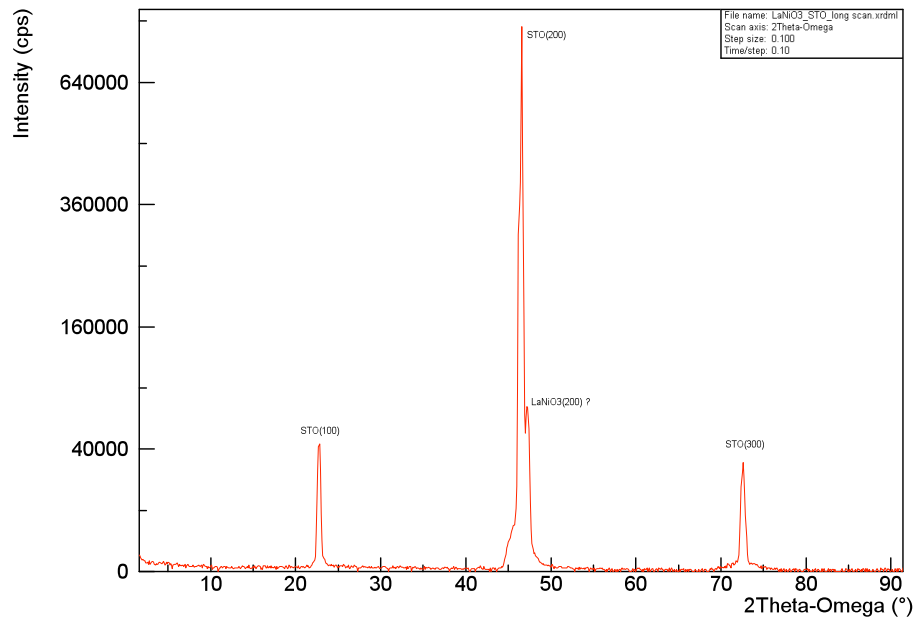


- *Changes in Pressure lead to reasonable changes in mass*
- *Initial variations have reasonable transients*
- *Can measure surface and bulk properties*

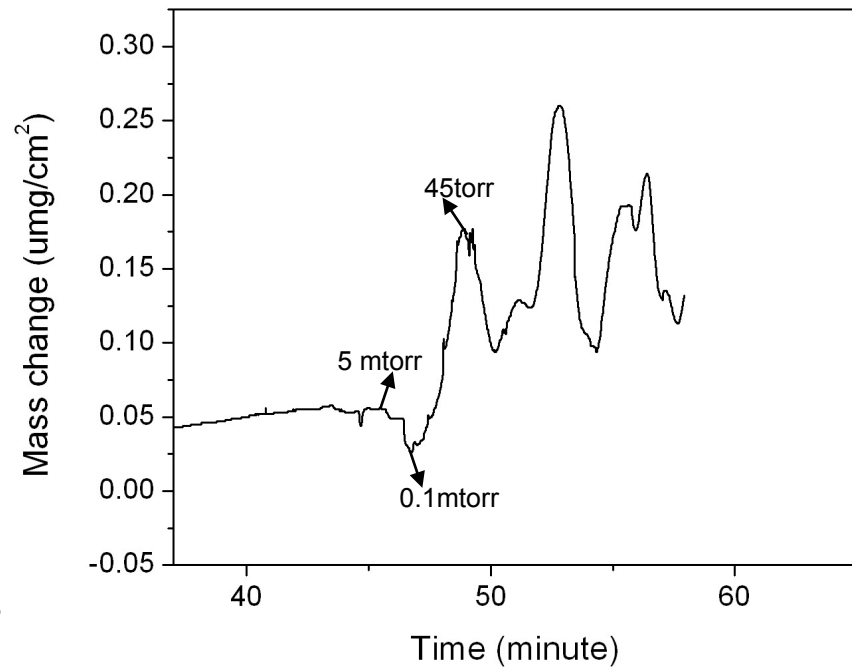
*Frequency Shifts occur on pressure changes: temperature or mass?*

# Initial Measurements on Single Crystal Sample

XRD of LNO on STO



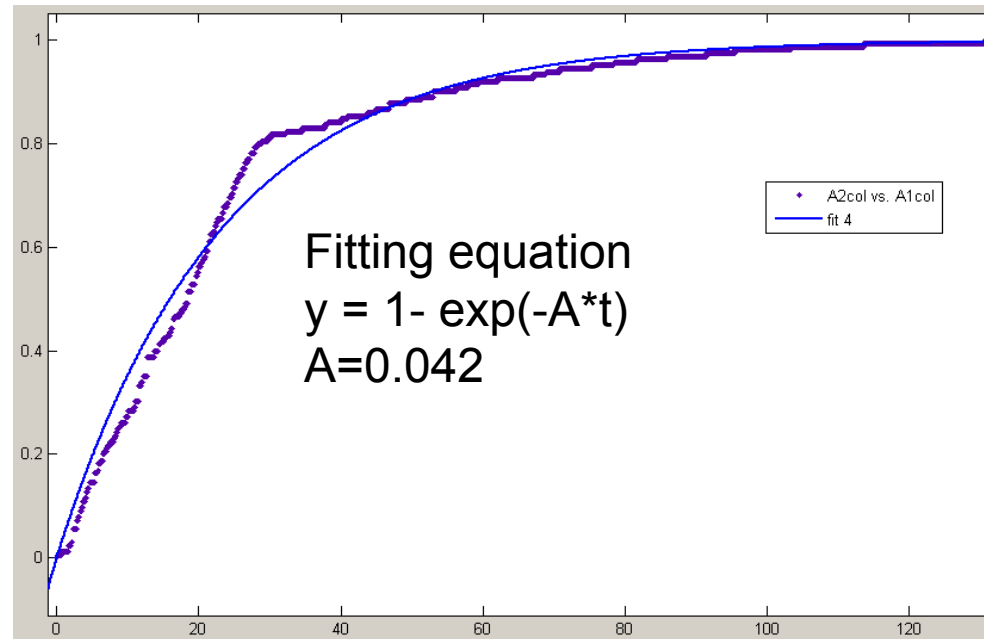
PCM with LNO deposited on STO(100)



- *Changes in Pressure lead to reasonable changes in mass*
- *Noise is a little higher with single crystal*
- *Procedure is promising for direct comparisons to APS work*

## Transient Measurements to Determine Surface Properties

Mass change vs. time when  $\text{PO}_2$  change from 0.3 mtorr to 185 mtorr at  $350^\circ\text{C}$



- transient measurement is not quite exponential, need more work
- for thin film where  $k_{\text{chem}} = A \cdot l_{\text{film}} = 0.042 \times 130\text{nm} = 5.88 \times 10^{-7} \text{ cm/s}$
- $k_{\text{chem}}$  for  $\text{La}_2\text{NiO}_{4+x}$  ceramics at this temperature is  $7 \times 10^{-7} \text{ cm/s}$   
(G .Kim et al Solid State Ionics 177(2006))

*PCM measurements can yield surface properties of Thin Films!*

## Determining Appropriateness of Measurements

- Oxygen vacancy in deposited LNO thin film
  - Thin film weight from G-PCM measurement:  $16 \times 10^{-6} \text{g}$
  - Thin film thickness 140nm
  - Total oxygen vacancy in this thin film if assuming it is  $\text{LaNiO}_{2.5}$ :  
 **$1.9 \times 10^{16}$**
- Measurement oxygen vacancy when  $\text{PO}_2$  change from 0.3 mtorr to 185 mtorr
  - Weight change from G-PCM measurement:  $0.056 \times 10^{-6} \text{g}$
  - Corresponding oxygen vacancy loss:  
 **$2.1 \times 10^{15}$**
- Summary
  - At 350°C, 1/10 possible oxygen vacancy change was observed in LNO film

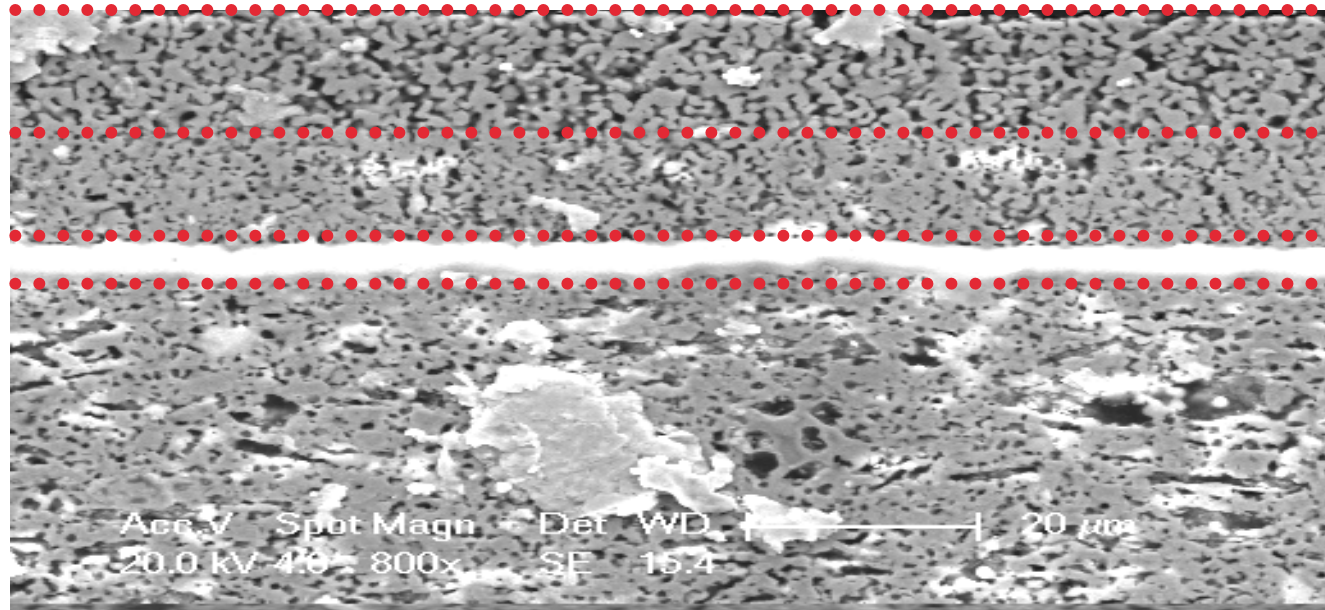
# Why Study Cathode Surfaces?

Current Collector  
Pores + (La,Sr)MnO<sub>3</sub>

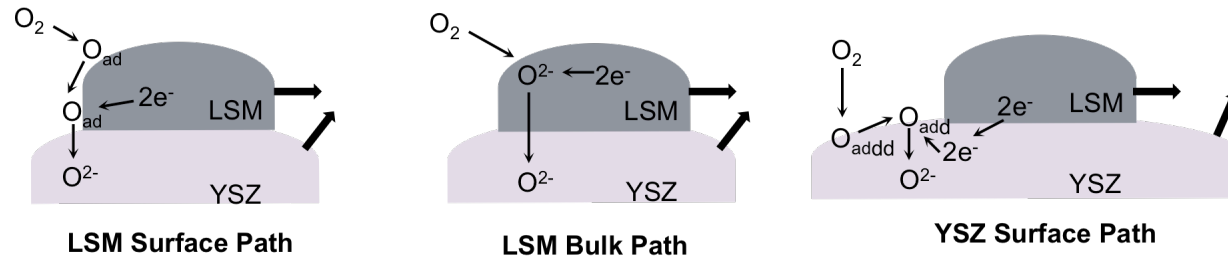
Active Cathode  
P + LSM + YSZ

Electrolyte (YSZ)

Anode  
P + YSZ + Ni



*The oxygen reduction reaction is surface specific and is related to two and three phase boundaries in SOFCs.*



***We don't understand Surfaces OR Internal Interfaces!***